

Electron Transport in Plasma-Produced, Disordered Nanocrystal Films

Uwe R. Kortshagen

Dept. of Mechanical Engineering, University of Minnesota

Funding:

NSF MRSEC DMR-1420013

DOE Center for Advanced Solar Photophysics

AOR MURI Grant W911NF-12-1-0407

Overview

- Introduction
- Plasma synthesis of nanocrystals
- Electronic transport in NC films (P-doped Si)
- Another try: ZnO NC films
- Semitransparent Luminescent Solar Concentrators
- Conclusions



On the market products



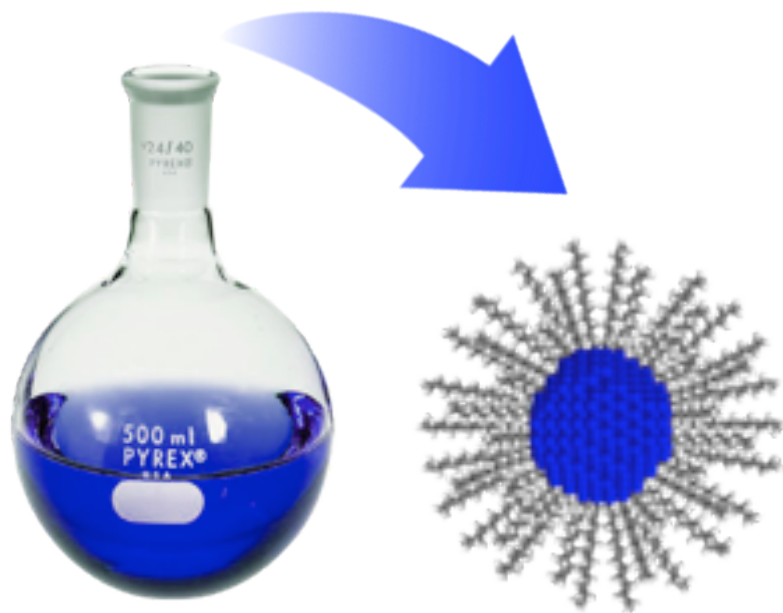
Samsung Quantum dot TV



DuPont-Innovalight Si ink

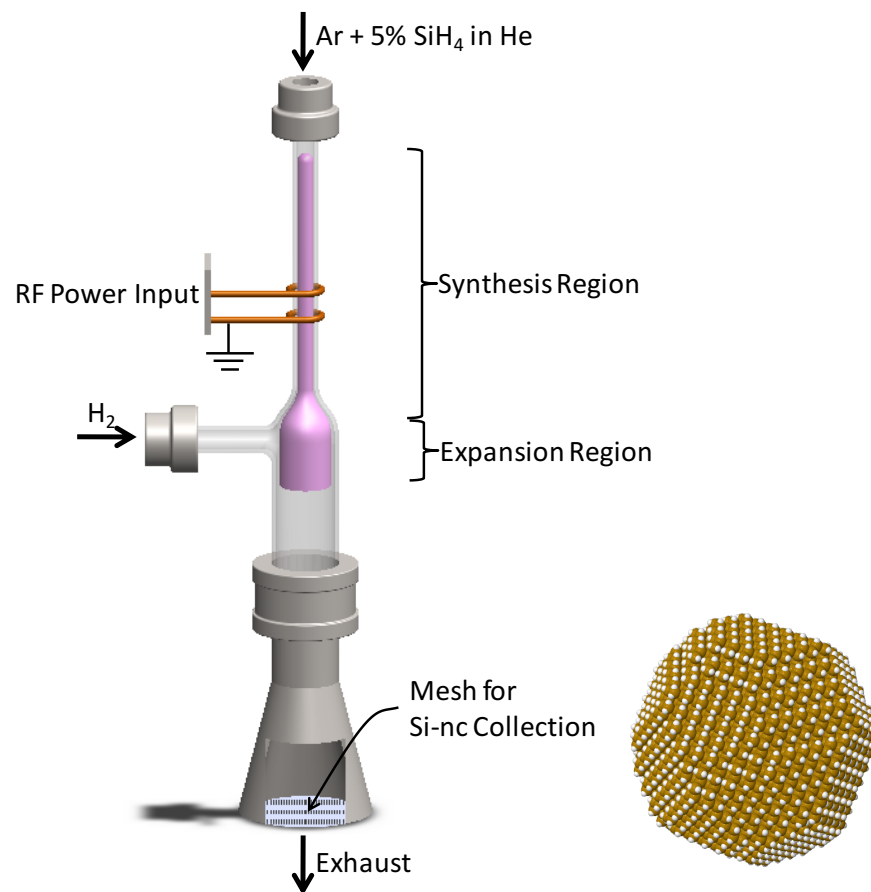
Quantum dot syntheses

Liquid Phase Synthesis



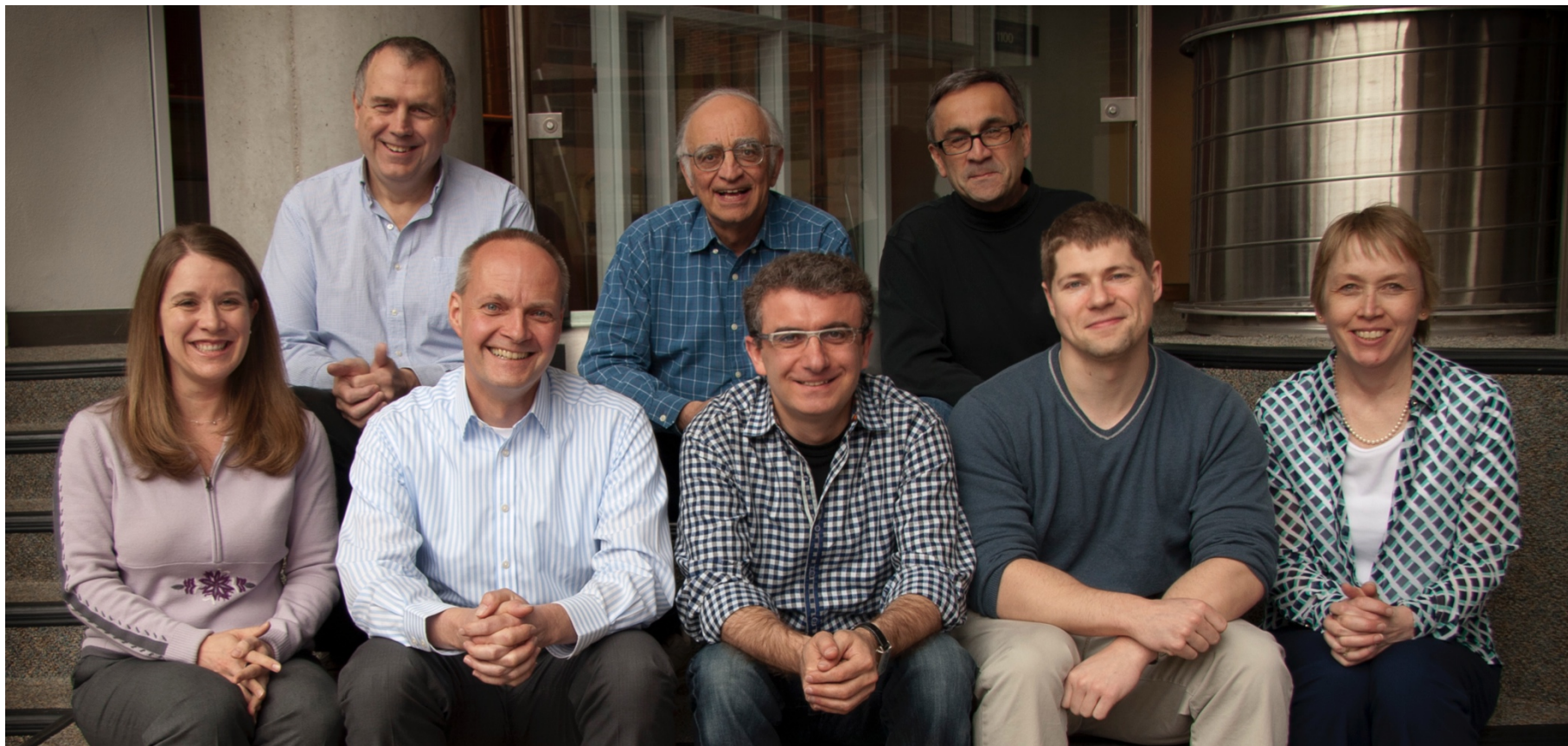
ionically bound NCs (PbX , CdX ; $\text{X}=\text{S}$, Se , Te)

Gas Phase Synthesis



covalently bound NCs (Si , Ge , nitrides,...)

MRSEC IRG-2: Sustainable Nanocrystal Materials

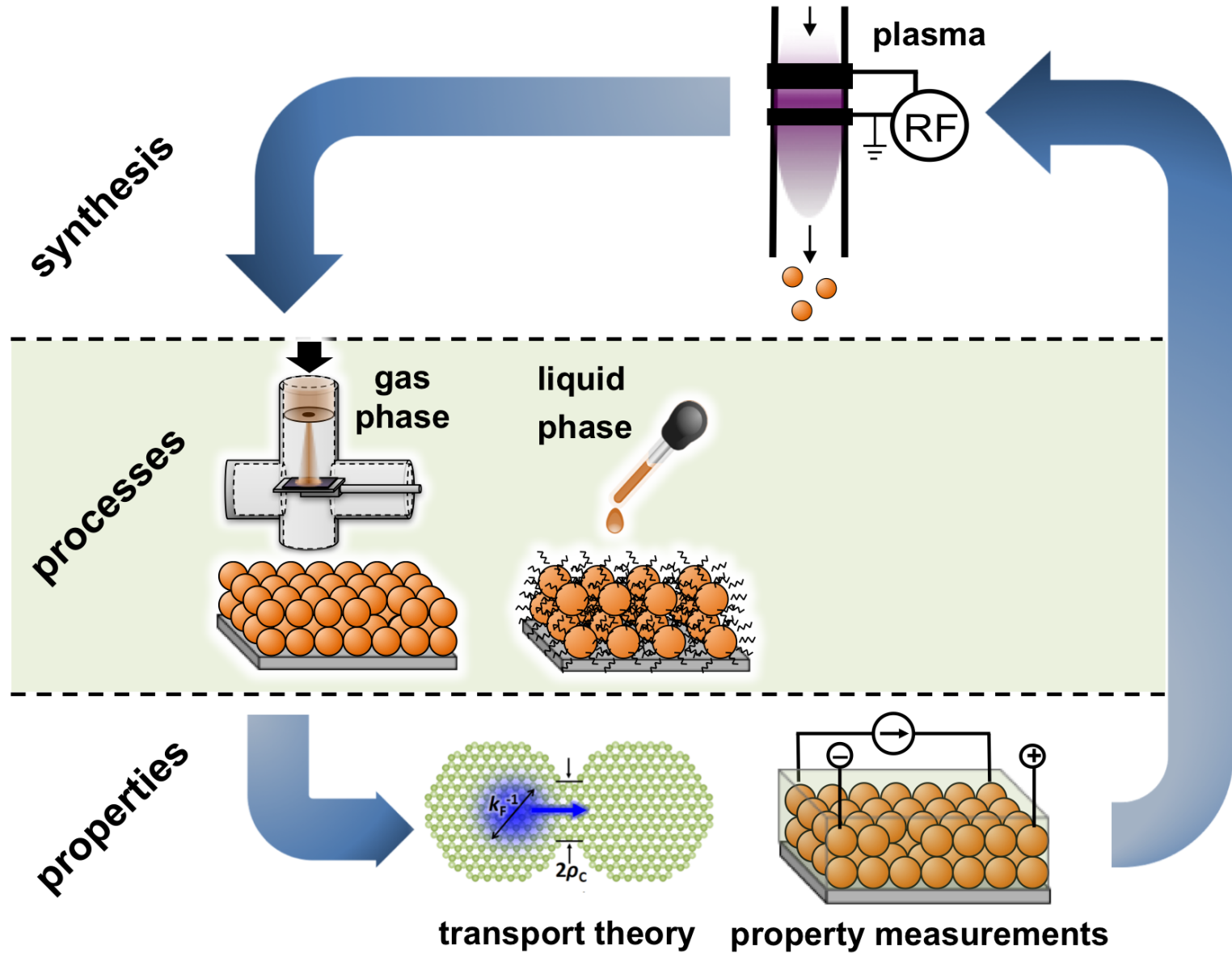


Stephen Campbell, Boris Shklovskii, Eray Aydil

Christy Haynes, Uwe Kortshagen, Andre Mkhoyan, Chris Hogan, Lorraine Francis



IRG activities





L. Mangolini

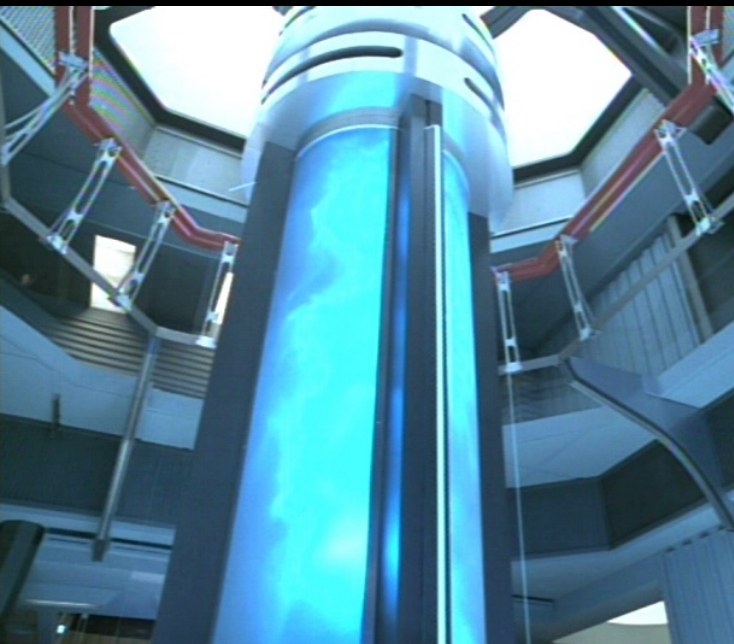


E. Thimsen

Plasma synthesis of nanocrystals



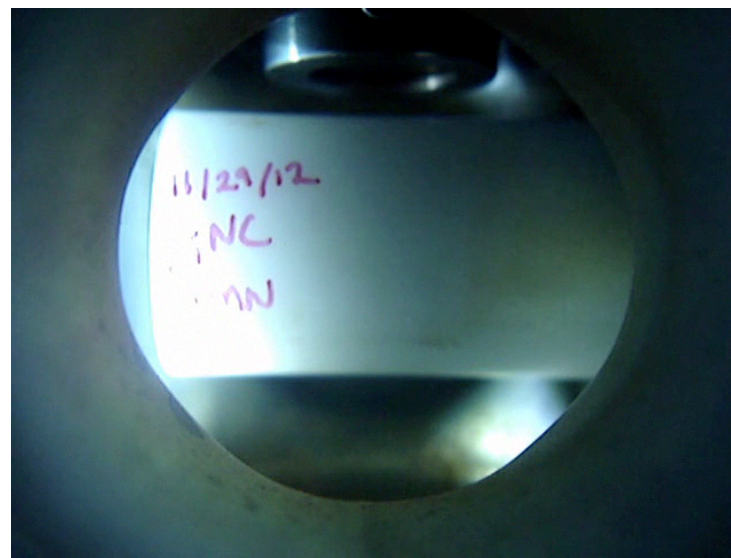
Plasmas: The medium of the future!



Plasmas synthesis of group IV nanocrystals

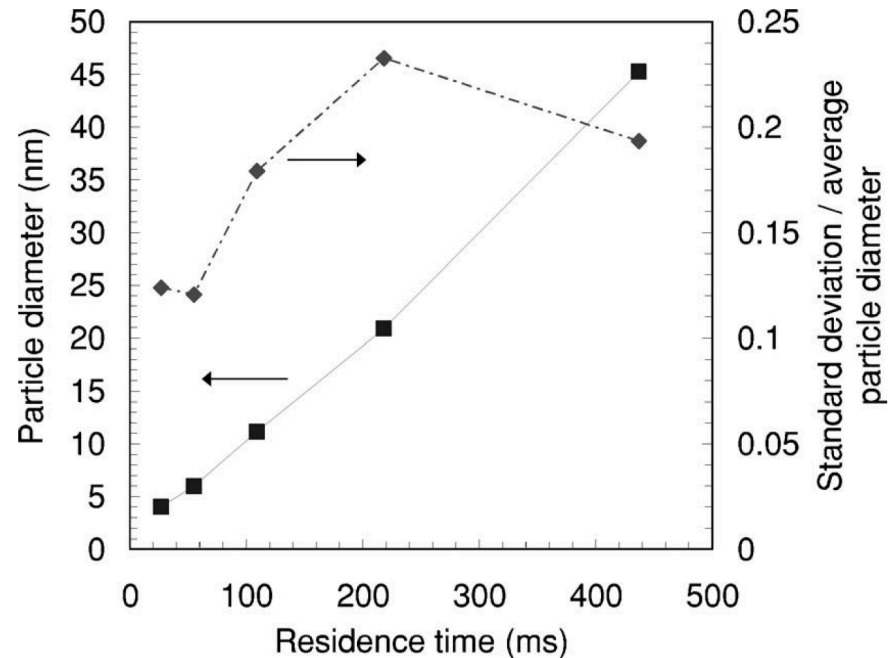
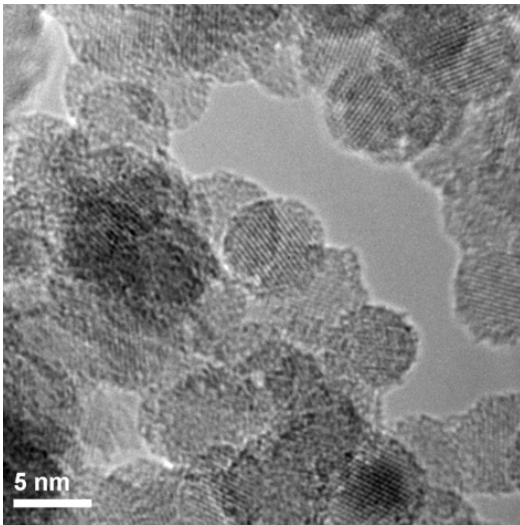


L. Mangolini, E. Thimsen and U. Kortshagen,
Nano Letters **5**(4), 655 (2005)



- gas pressure: few 100 Pa
- gas temperature: ~300-500 K
- electron temp.: ~30,000-50,000 K
 (3-5 eV)
- ionization fract.: ~10⁻⁵

Plasmas synthesis of group IV nanocrystals



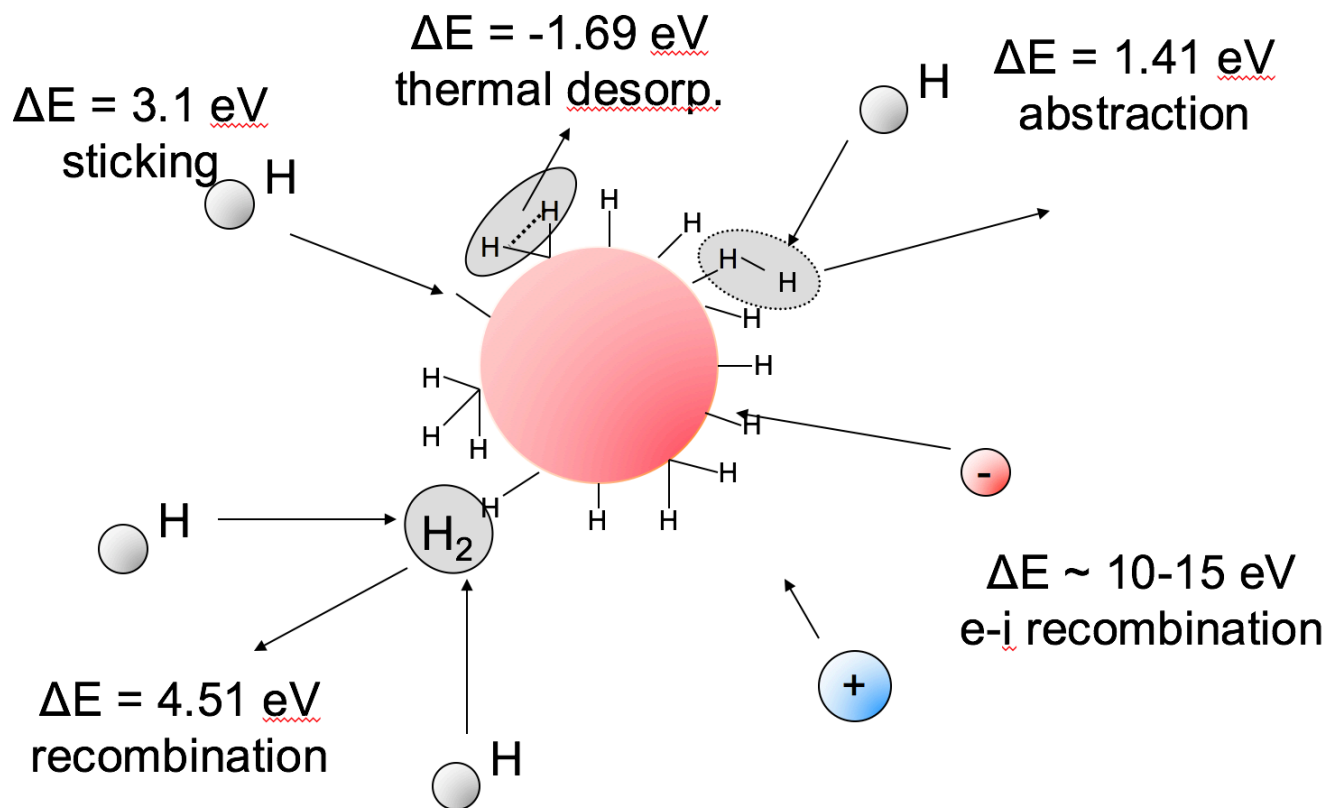
R. Gresback, Z. Holman, U. Kortshagen, Appl. Phys. Lett. **91**, 093119 (2007) (for Ge NCs from GeCl_4)

- materials that require high temperature
- particle size control through residence time
- relatively good monodispersity

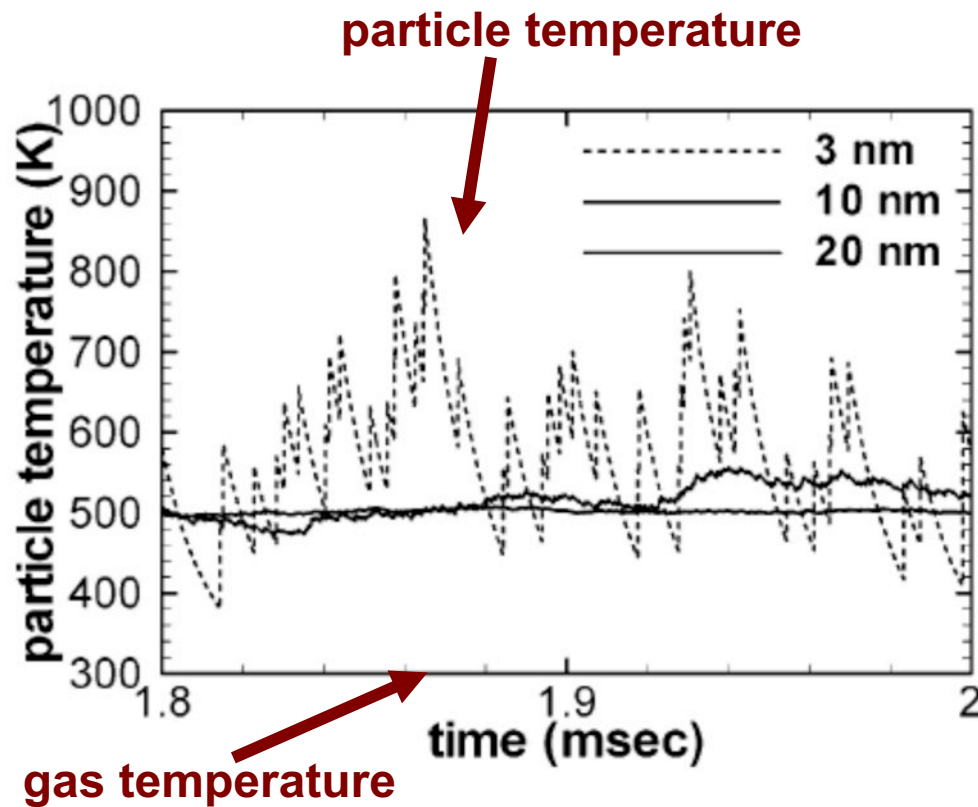
L. Mangolini et al., Nano Letters (2005)



Heating of NCs in plasmas



Heating of NCs in plasmas

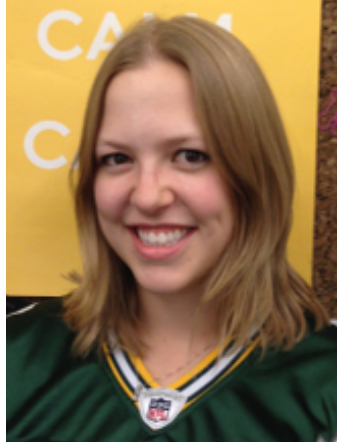


L. Mangolini et al., Nano Letters (2005)





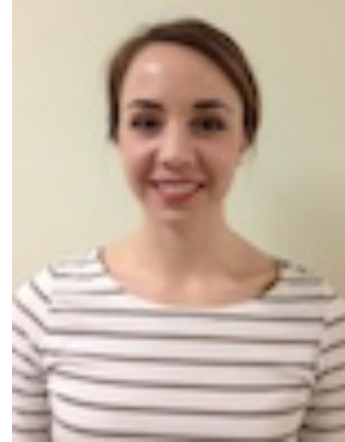
David Rowe



Katelyn Schramke



Nic Kramer



Katharine Hunter



Nick Bedford
(NIST, Boulder)

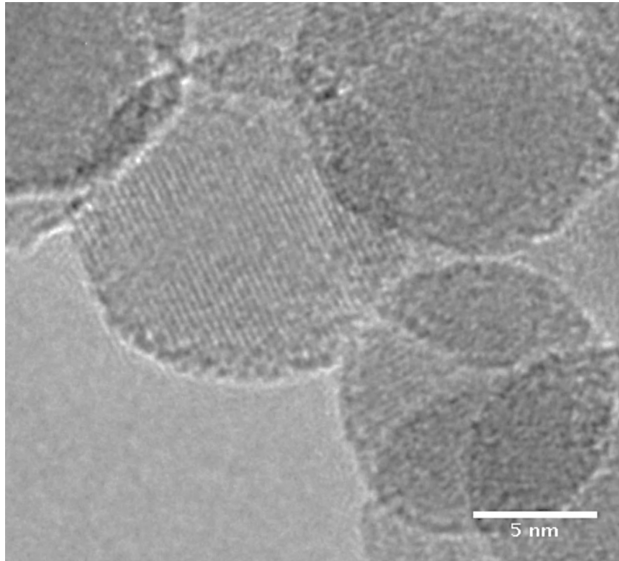
Nanocrystal doping and plasmonics



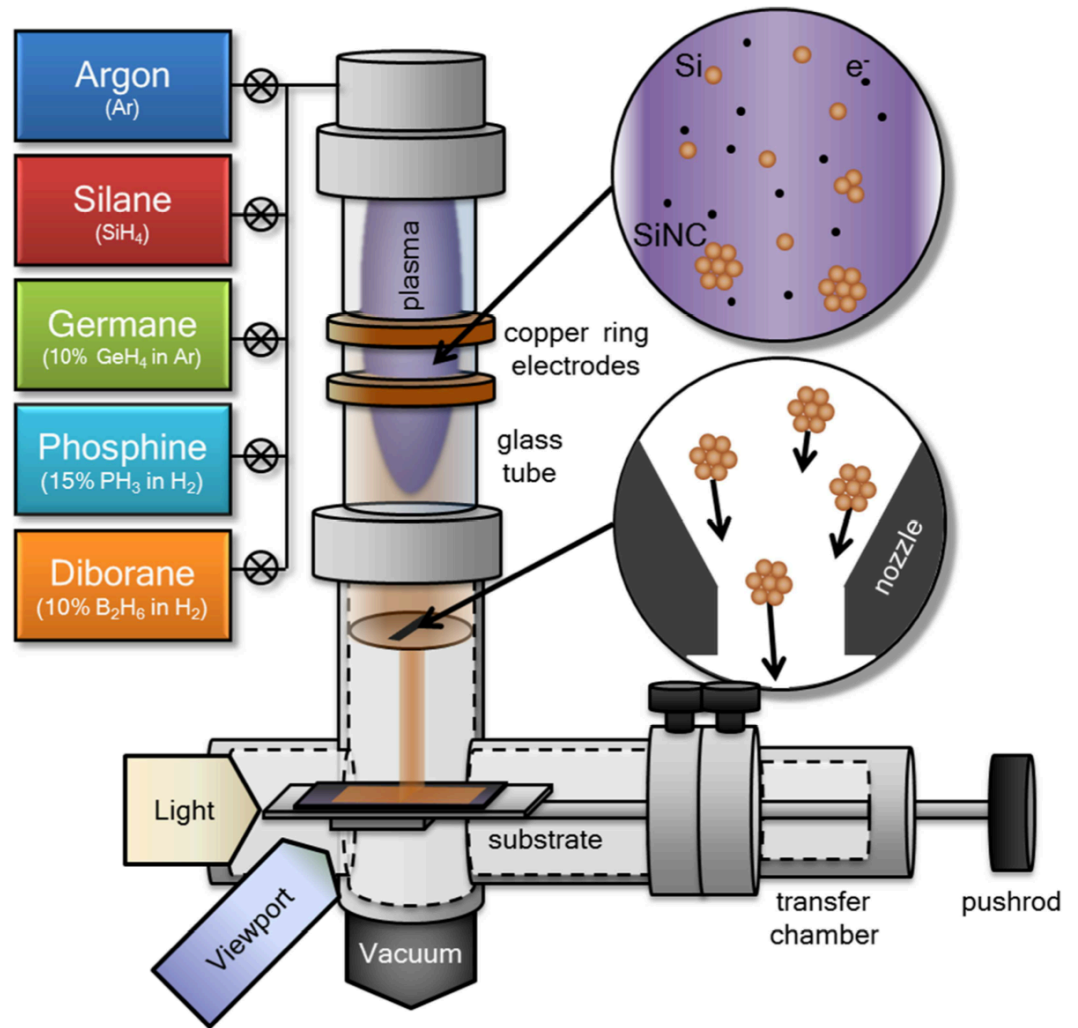
Not this kind of plasma doping!



Doping Si nanocrystals



Nanoparticle size: ~ 8 nm

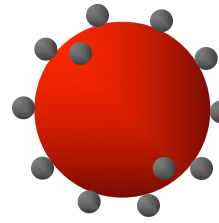


D. Rowe, Ph.D. thesis, UMN

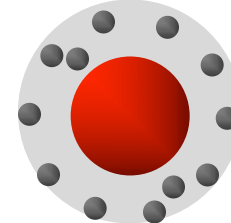


First attempts at plasma doping

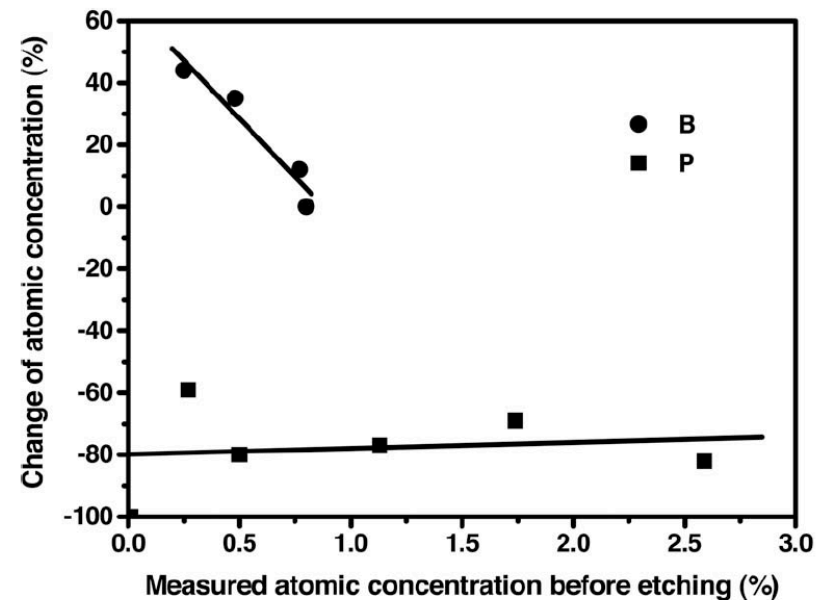
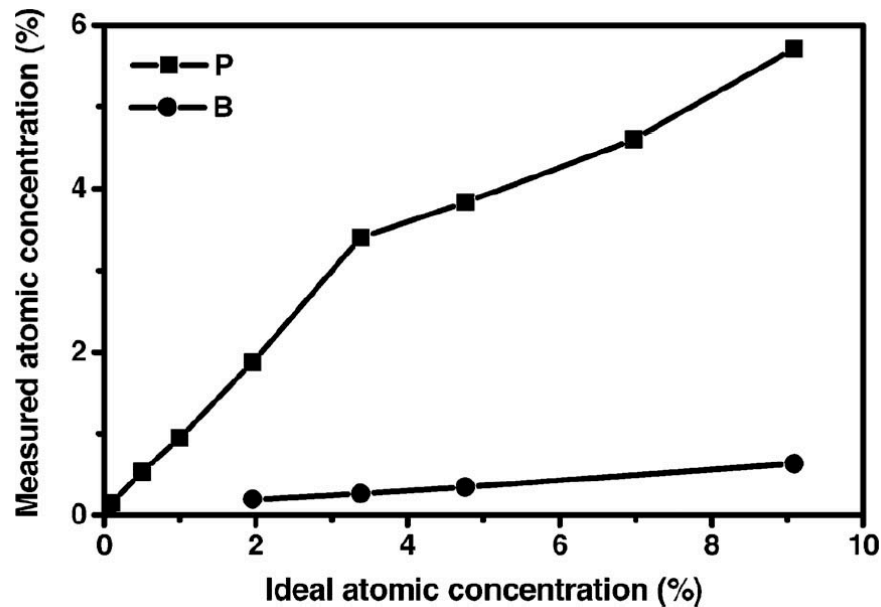
as produced



oxidized



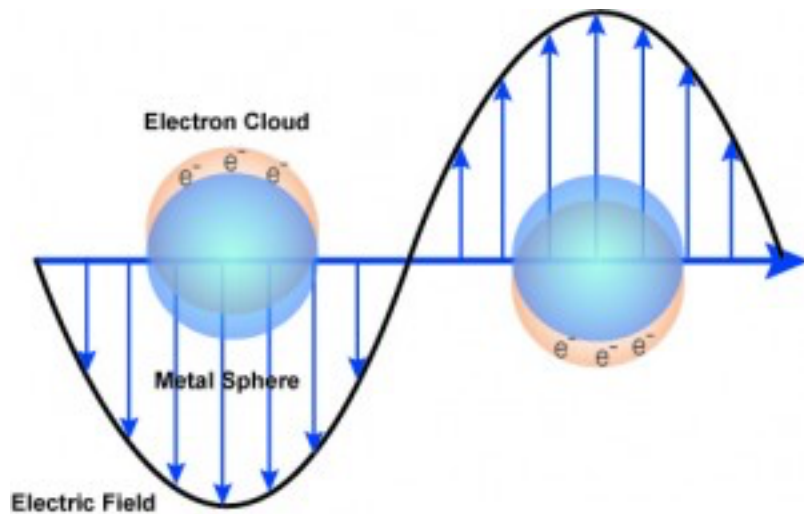
HF etched



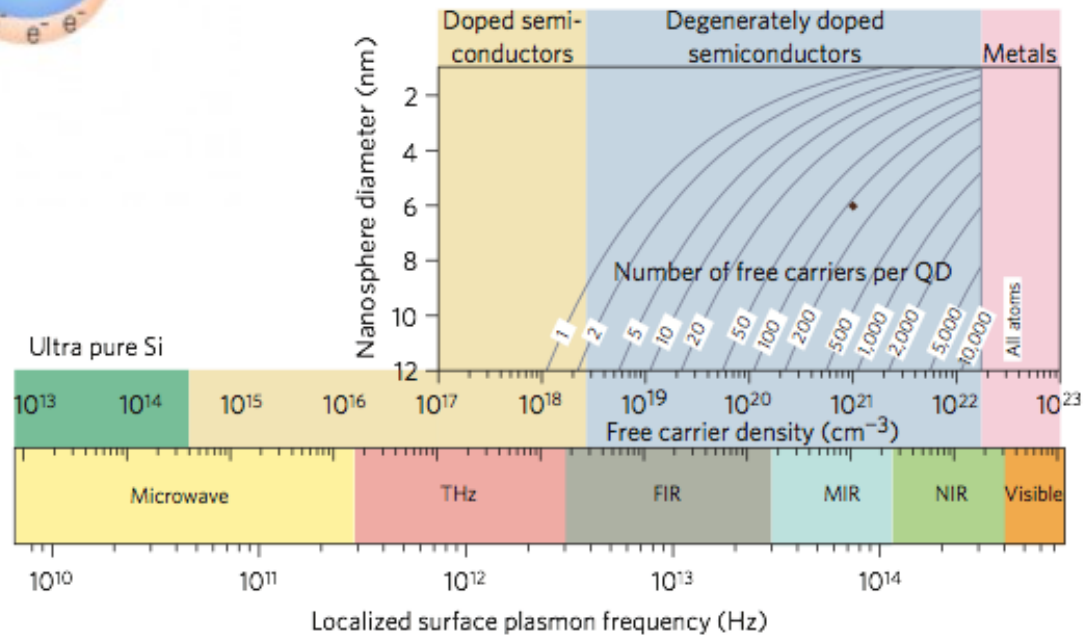
X. D. Pi and R. Gresback, R. W. Liptak, S. A. Campbell, U. Kortshagen, Appl. Phys. Lett. **92**, 123102 (2008).



Doped nanocrystals as IR absorbers



www.nanocomposix.com

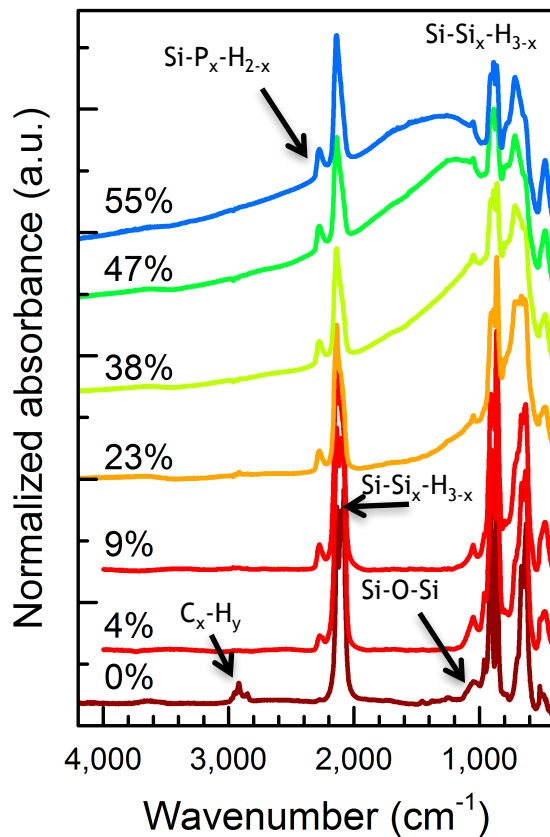


J.M. Luther, P.K. Jain, T. Ewers, and P. Alivisatos, Nature Materials 10, 361-6 (2011).

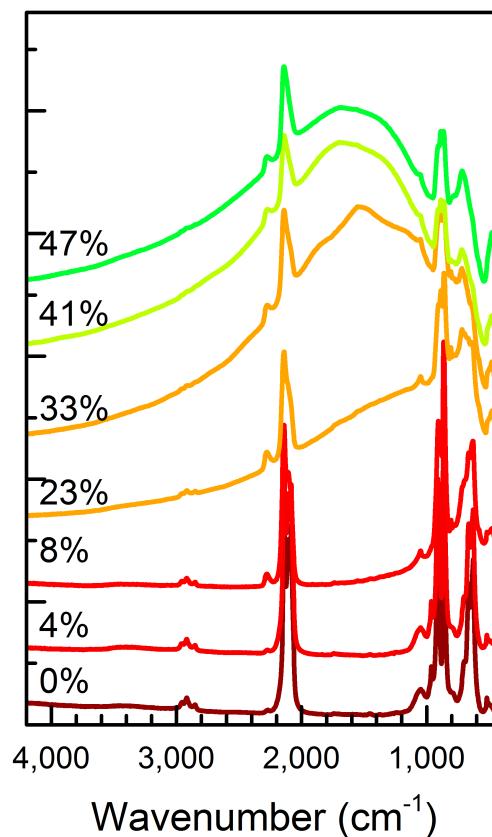


Si NC LSPR in IR

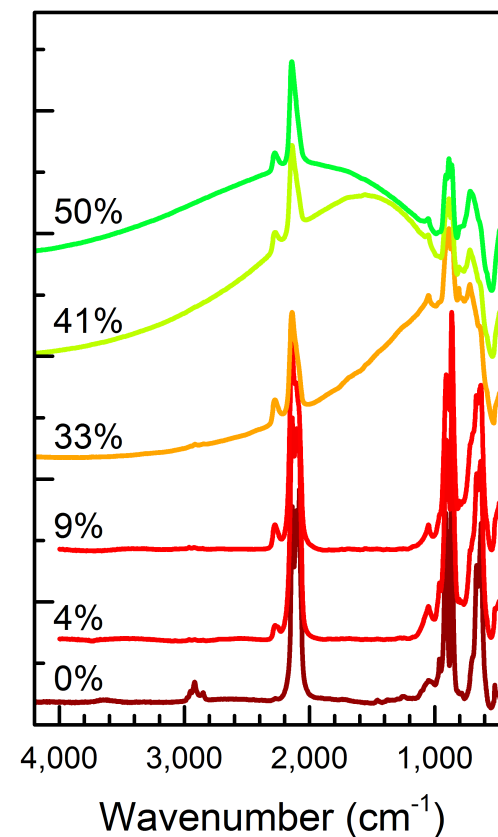
P = 0.8 Torr



P = 1.2 Torr



P = 1.6 Torr

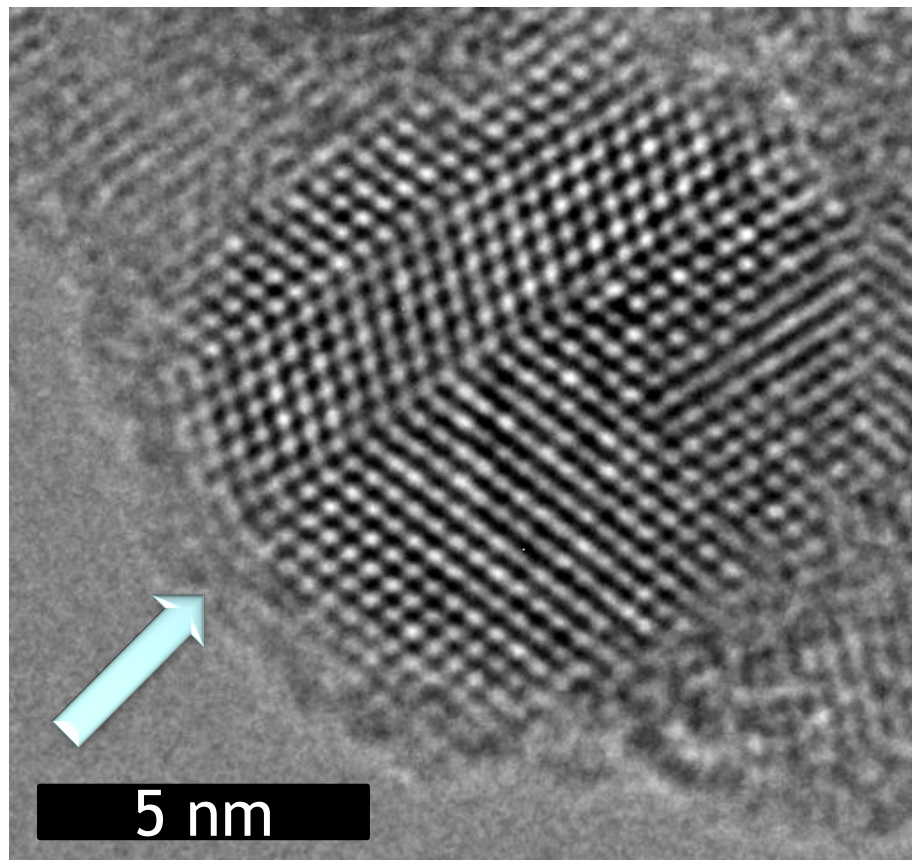
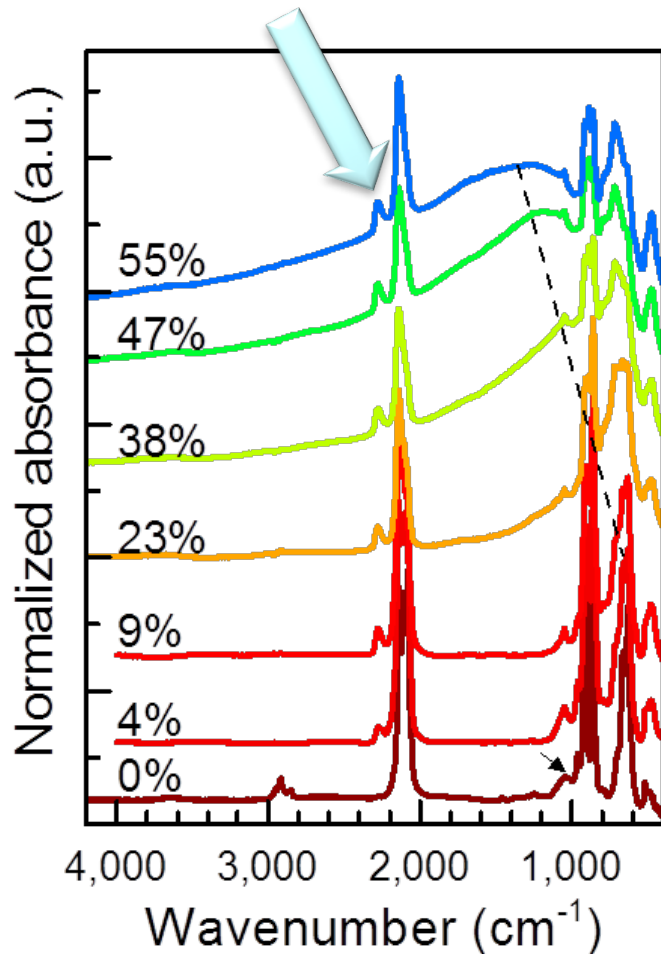


$$X_{\text{PH}_3} = [\text{PH}_3]/([\text{PH}_3]+[\text{SiH}_4])\times 100\%$$

D. J. Rowe, J. S. Jeong, K. A. Mkhoyan, and U. R. Kortshagen, Nano Letters **13**, 1317 (2013)

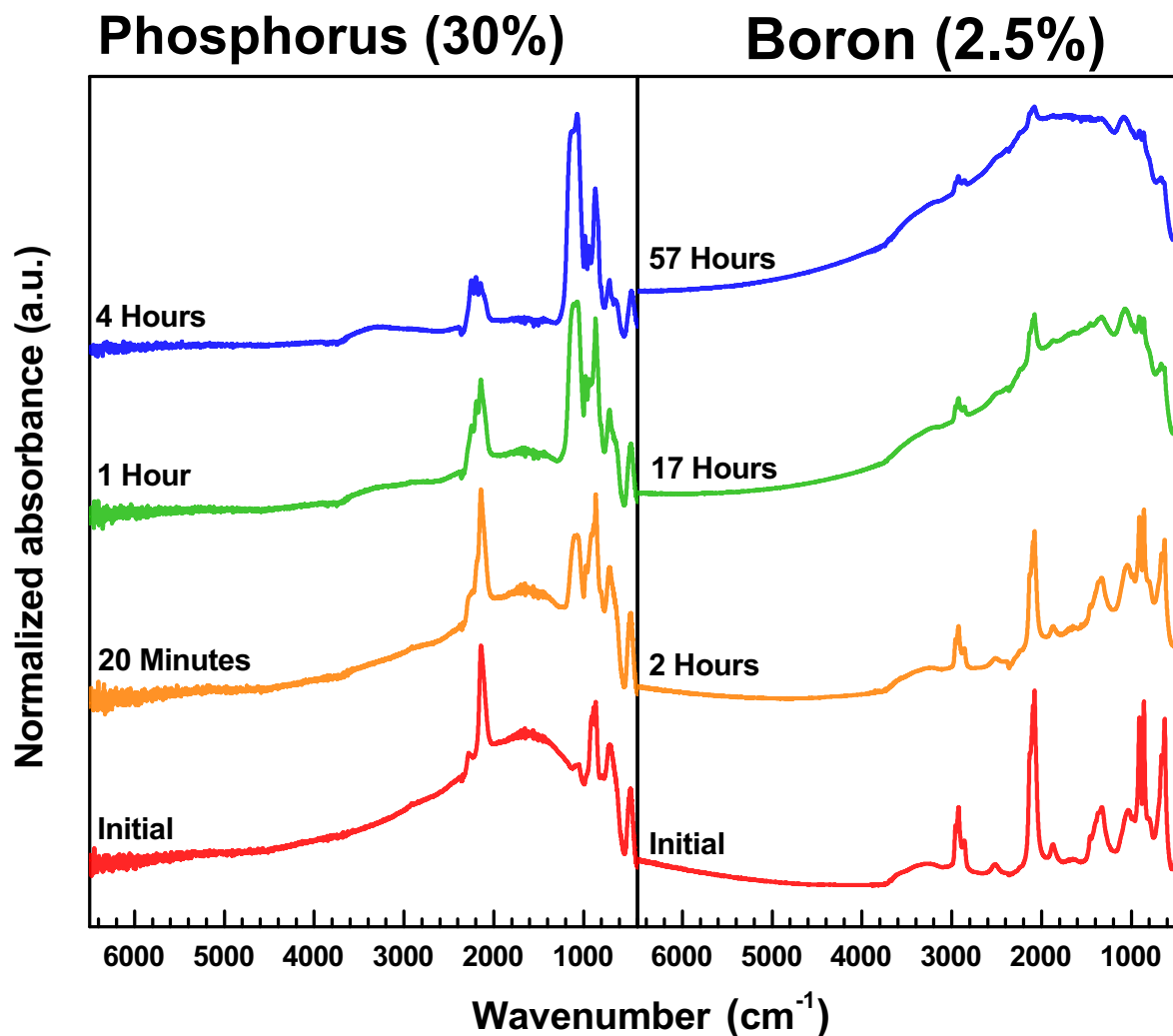


Hypothesized location of dopant...



LSPR observation indicates some P in the NC core... but where's the rest?

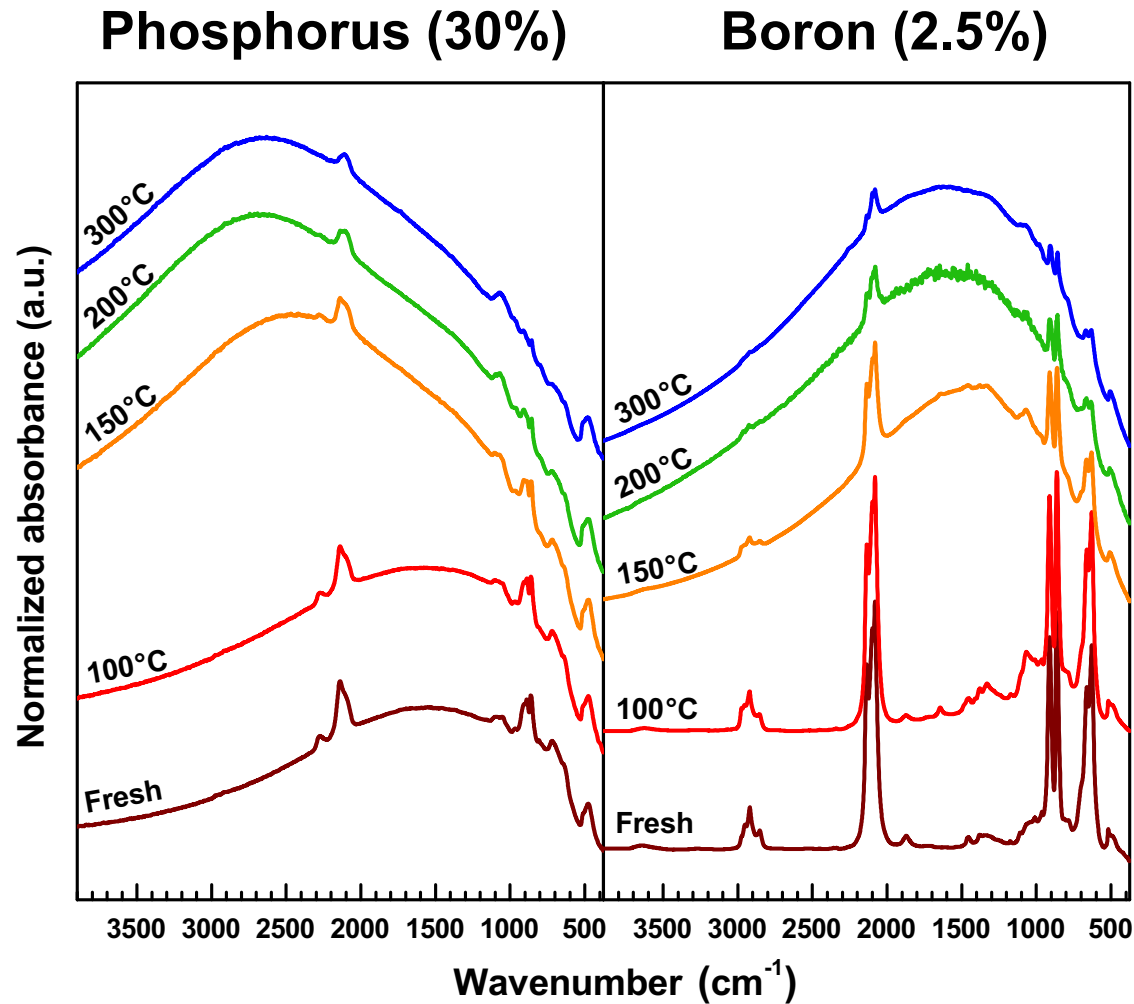
Influence of surface: oxidation



Kramer, N. J.; Schramke, K. S.; Kortshagen, U. R. *Nano Letters*, **15** (8), 5597-5603, (2015)



Plasmonic response of doped NCs



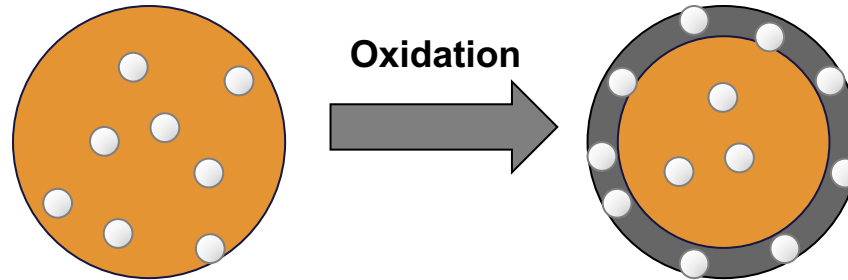
D. J. Rowe, J. S. Jeong, K. A. Mkhoyan, and U. R. Kortshagen, *Nano Letters* **13**, 1317 (2013)

Kramer, N. J.; Schramke, K. S.; Kortshagen, U. R. *Nano Letters*, **15** (8), 5597-5603, (2015)

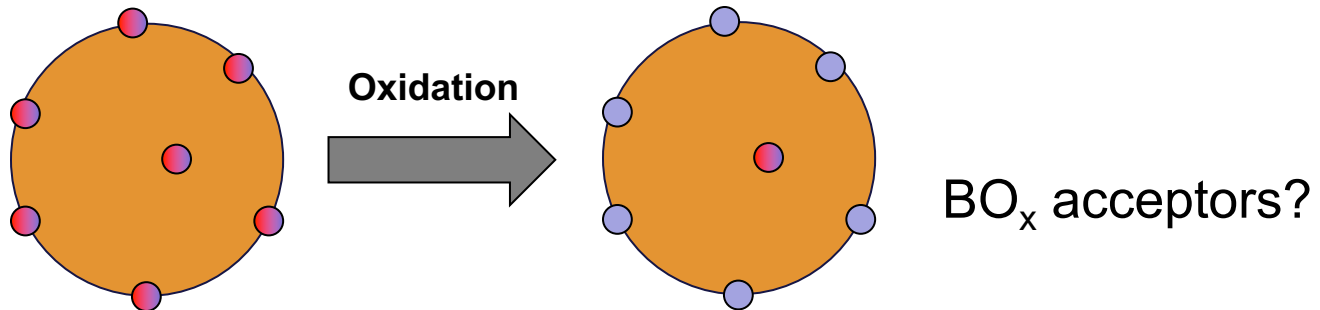


Role of surface in Si NC plasmonics

- P-doped Si NCs: substitutional P doping with trap generation at Si/SiO_x interface



- B-doped Si NCs: in addition to substitutional B, likely surface doping potentially through BO_x groups



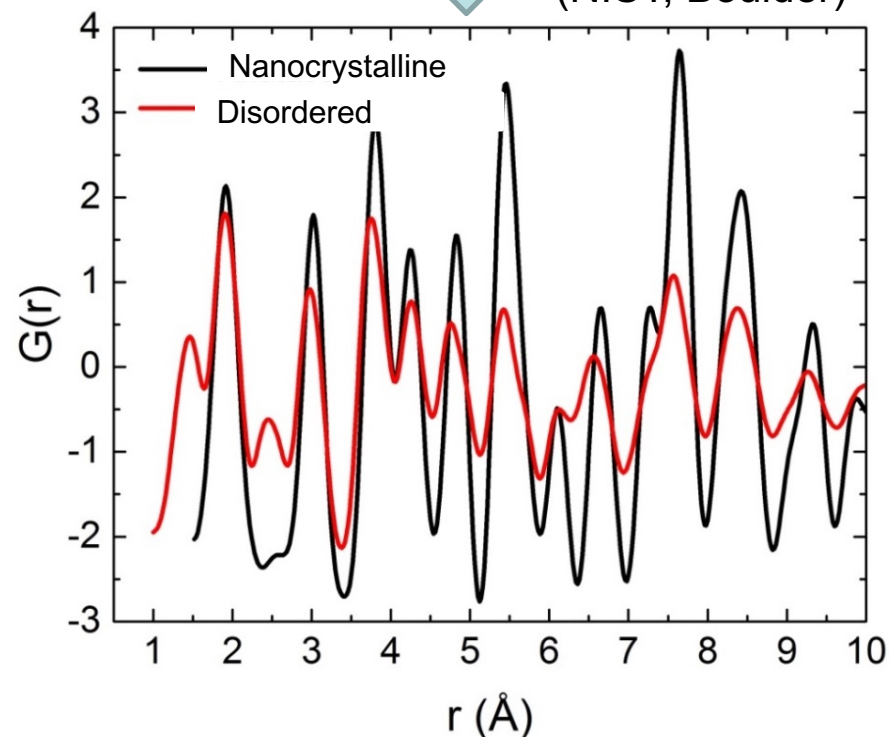
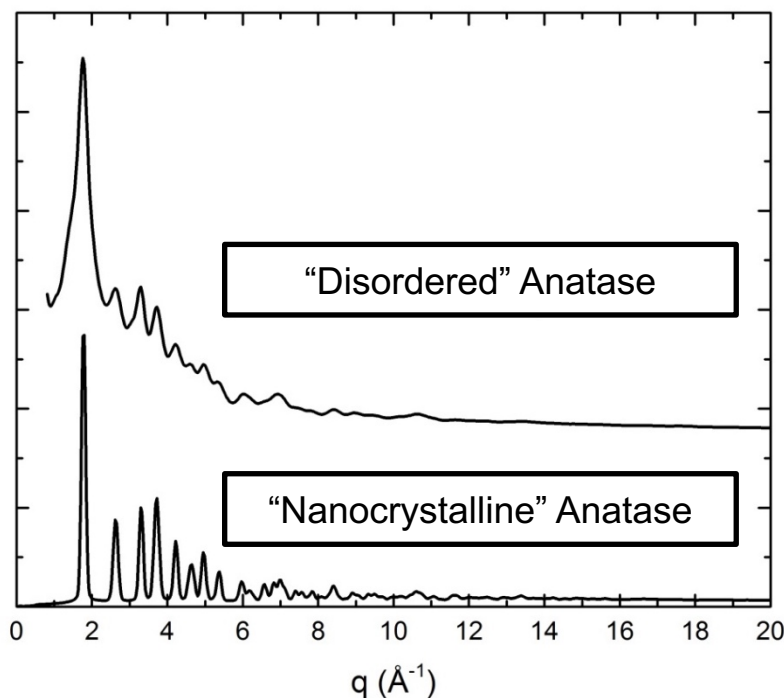
Pair distribution function analysis

- Atomic pair distribution function (PDF) analysis
→ Fourier transform of high energy XRD pattern
into atomic pair distances

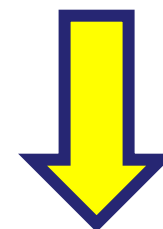
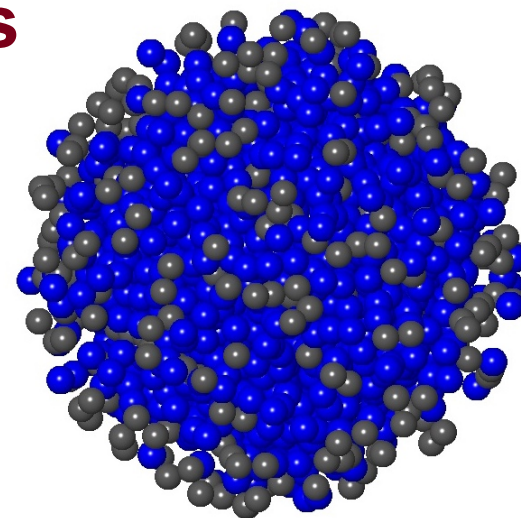
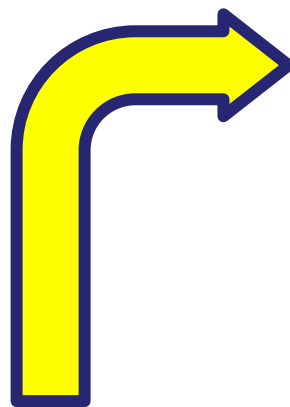
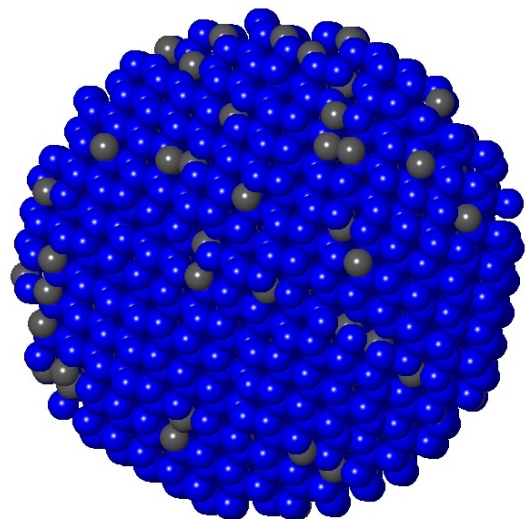
$$G(r) = \left(\frac{2}{\pi}\right) \int_{Q=0}^{Q_{\max}} Q[S(Q) - 1] \sin(Qr) dQ$$



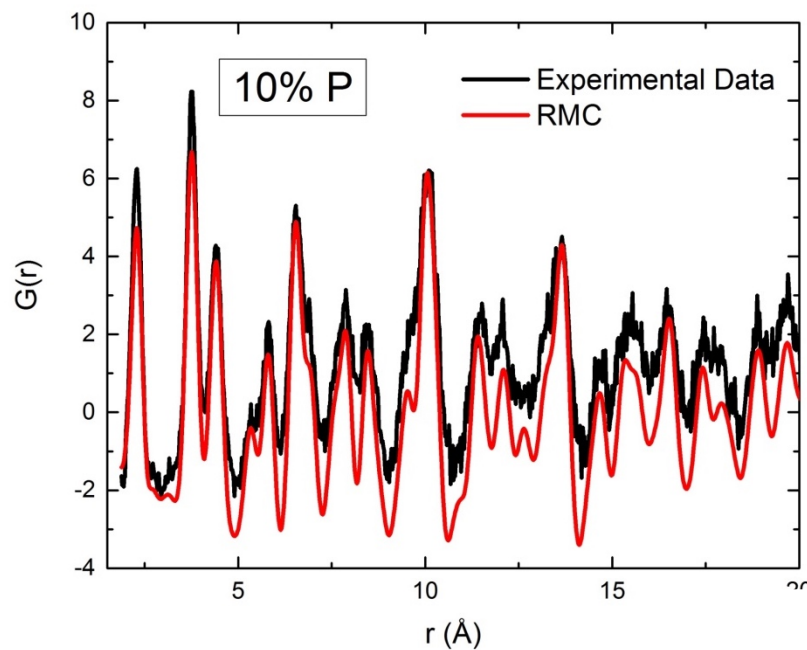
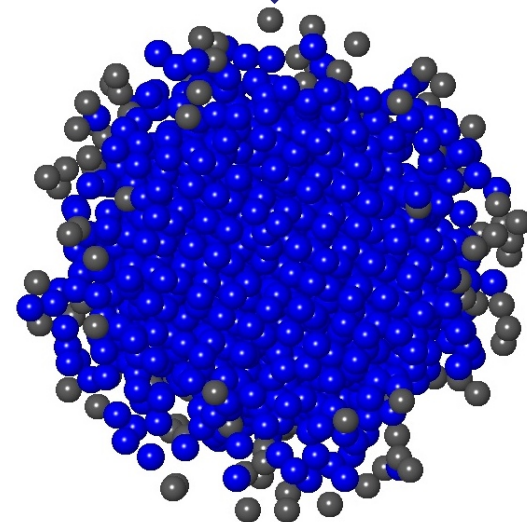
Nick Bedford
(NIST, Boulder)



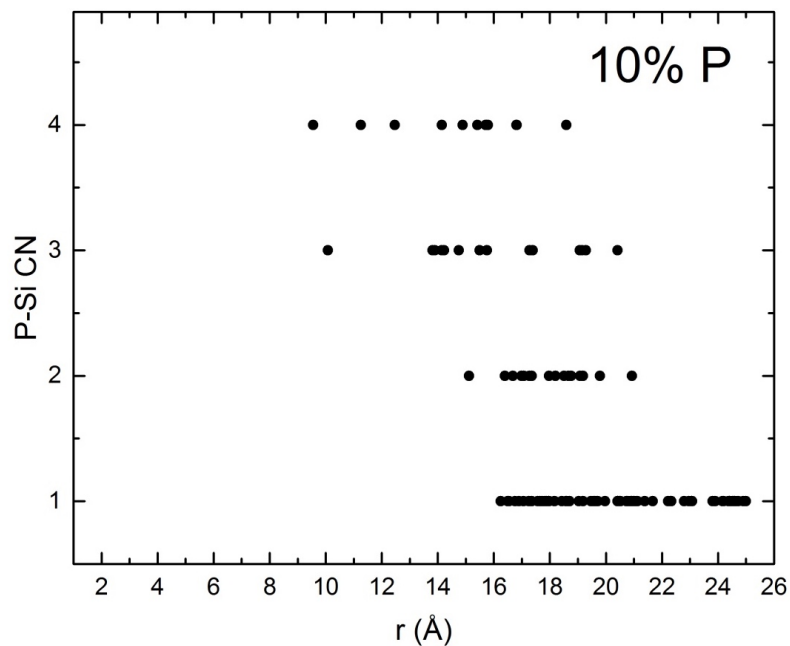
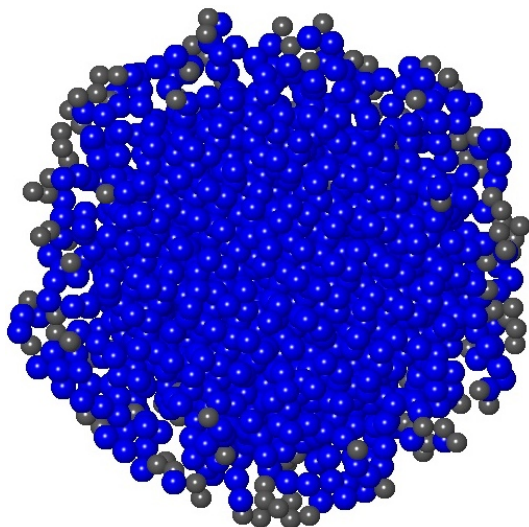
RMC of doped Si NCs



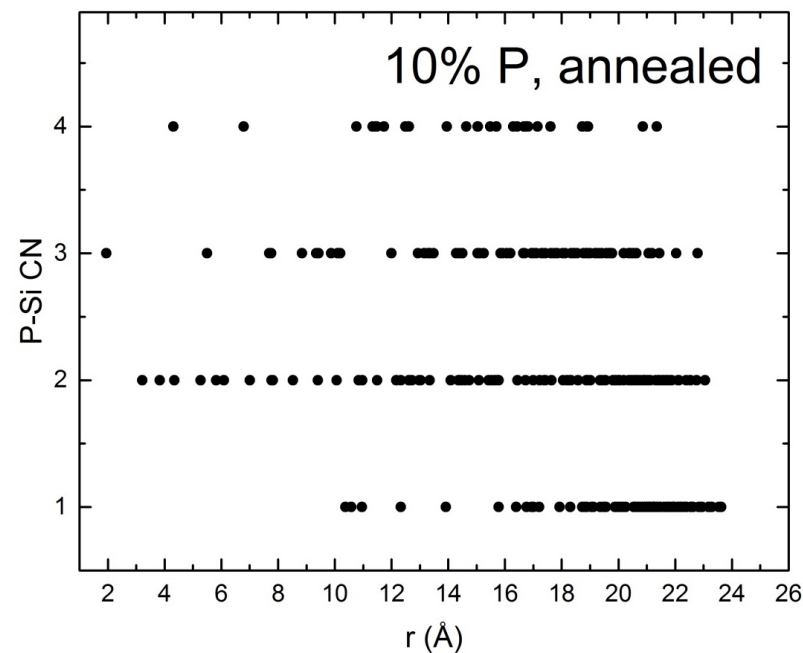
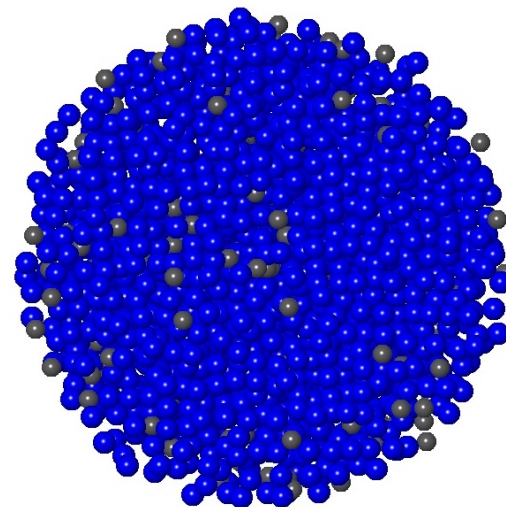
cross
section



10% P-doped Si NCs



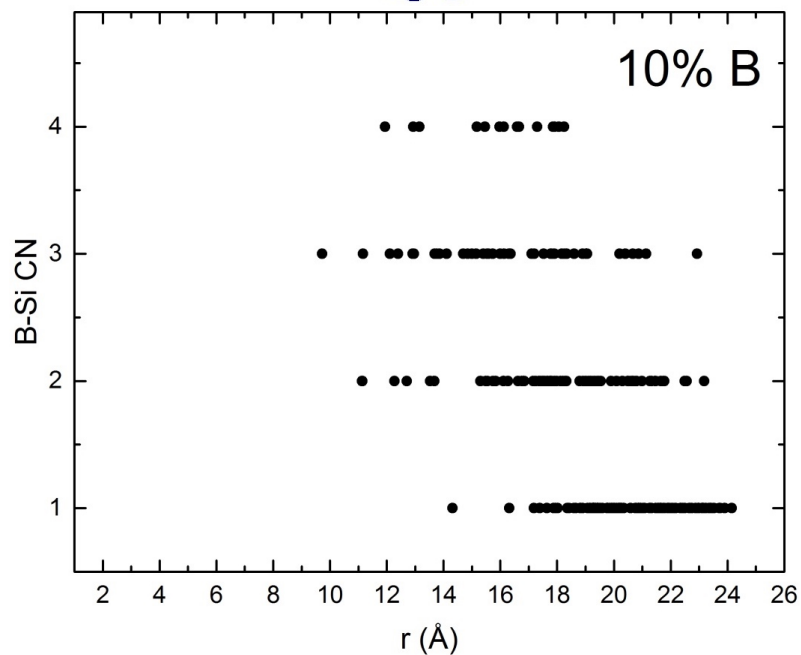
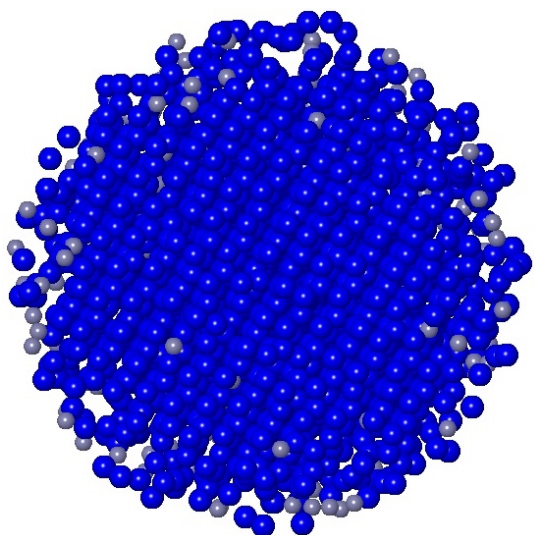
as deposited



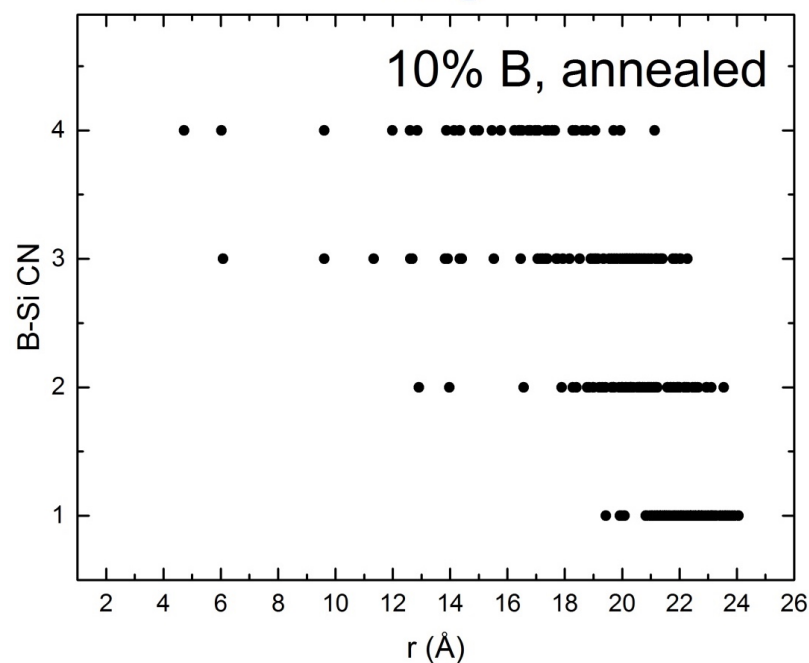
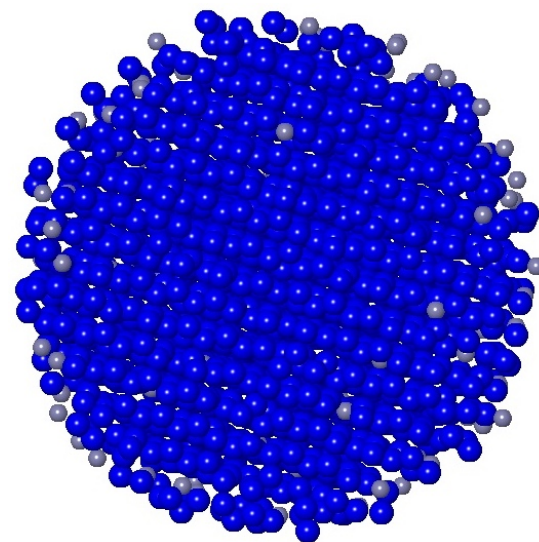
annealed at 200 °C, 30 min



10% B-doped Si NCs



as deposited



annealed at 200 °C, 30 min





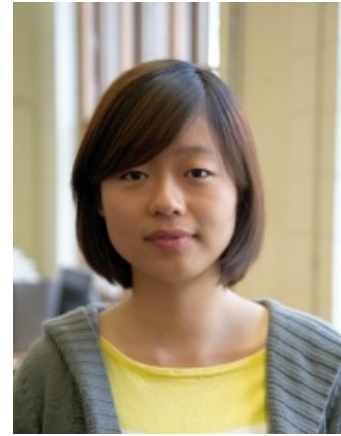
Ting Chen



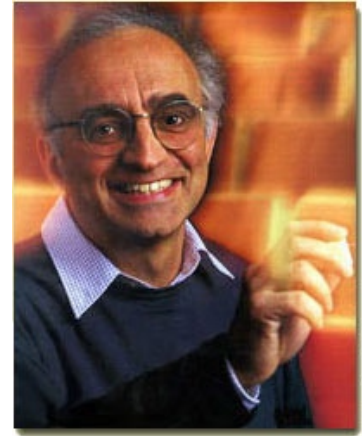
Nic Kramer



Konstantin Reich



Han Fu

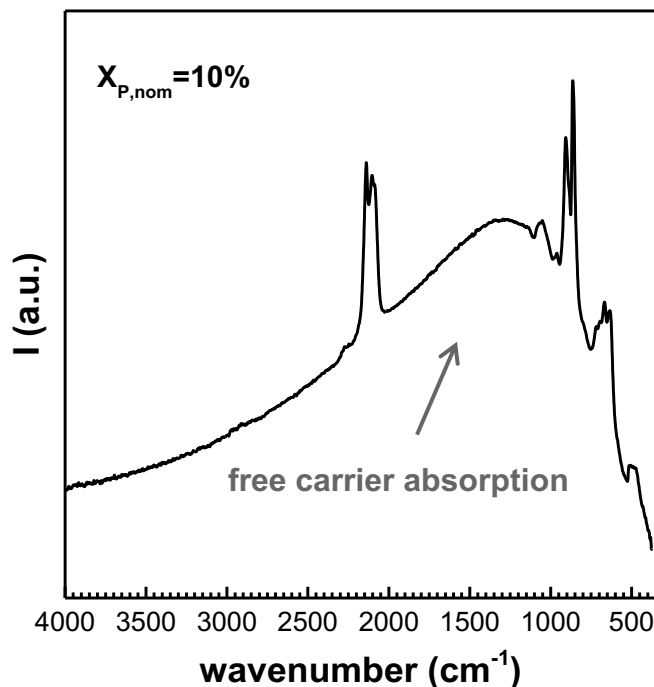


Boris Shklovskii

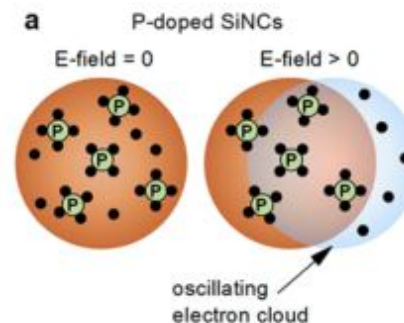
Electronic transport in nanocrystal films



Free electrons in P-doped Si NCs



Localized surface plasmon resonance (LSPR)



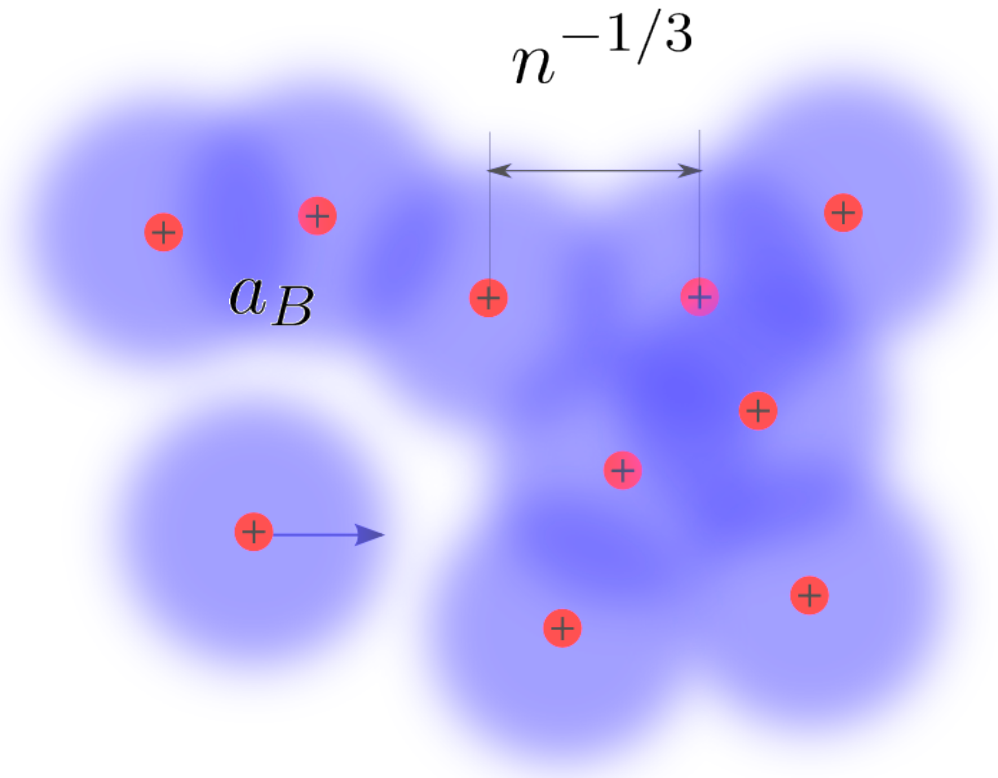
$$f_{LSPR} = \frac{1}{2\pi} \sqrt{\frac{n_{fc} e^2}{\epsilon_0 m_e^* (\epsilon_{Si} + 2\epsilon_m)}}$$

$$n_{fc} > 2.2 \times 10^{19} \text{ cm}^{-3}$$

$X_{P, nom}$ (%)	d (nm)	n (10^{20} cm^{-3})	N_P	$N_{P, active}$	$N_{P, active}/N_P$ (%)
1	8.1	-	65	-	-
2	8.0	-	110	-	-
3	8.0	-	210	-	-
5	8.0	1.9	320	51	16
10	7.5	2.4	442	53	12
20	7.1	2.8	644	52	8



Metal to insulator transition in bulk semiconductors



Metal-Insulator Transition in bulk semiconductors

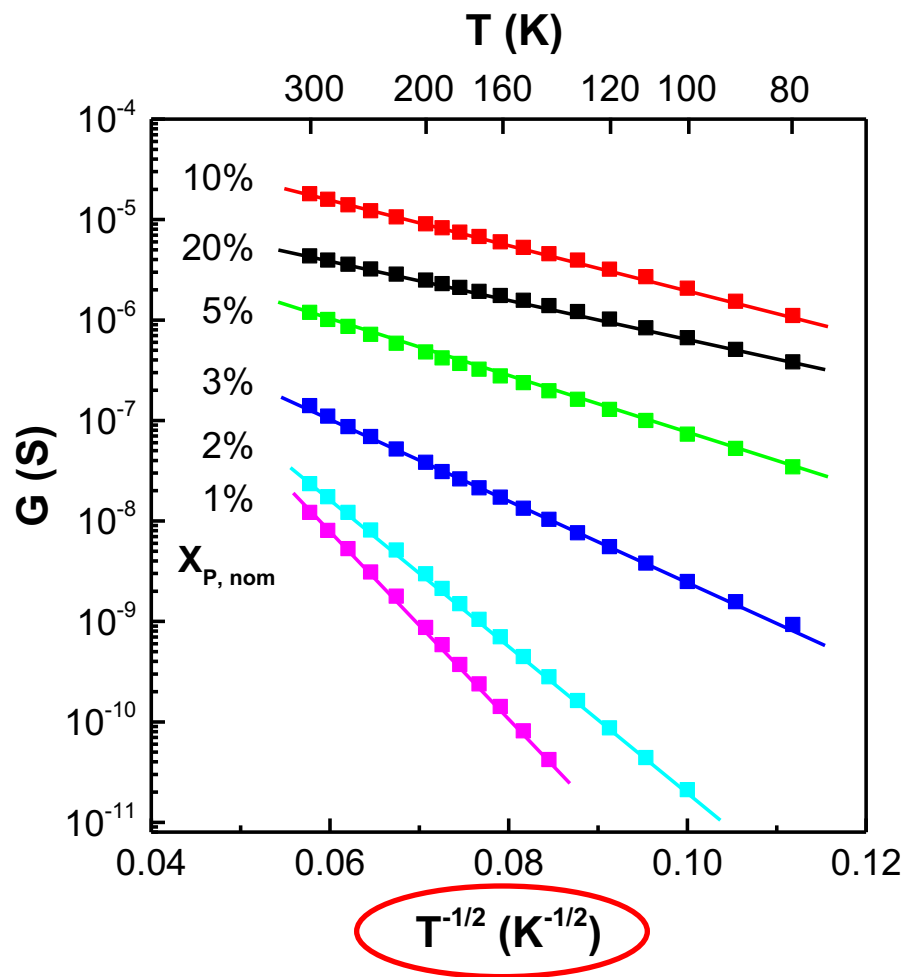
Mott criterion: $n_M a_B^3 \approx 0.02$

Si: $n_M \approx 3 \times 10^{18} \text{ cm}^{-3}$

CdSe: $n_M \approx 2 \times 10^{17} \text{ cm}^{-3}$



How far do electrons hop?



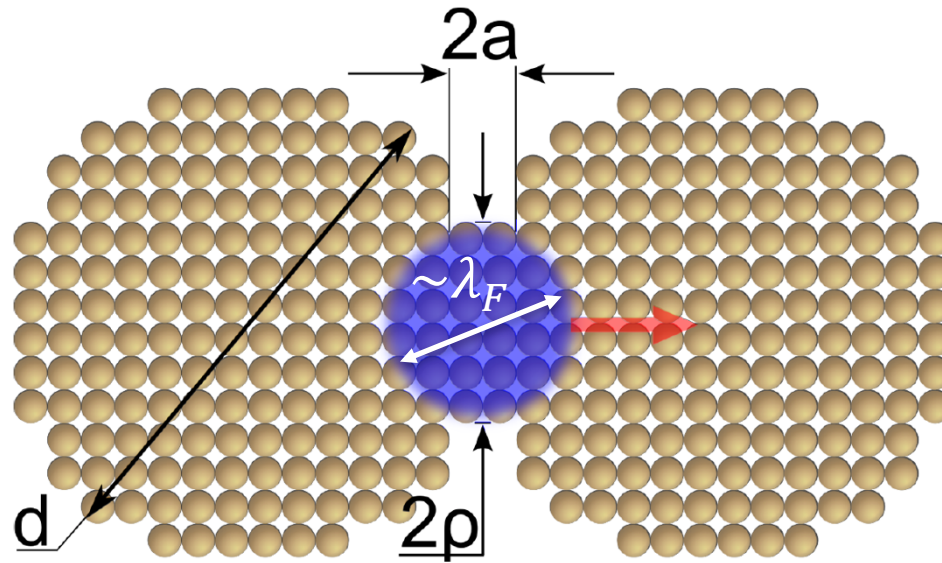
Characteristic temperature:

$$T_{\text{ES}} = \frac{2.8e^2}{4\pi k_B \epsilon \xi}$$

Localization Length



Theory of metal-insulator transition in NC films



$$k_F \rho \approx 2$$

or

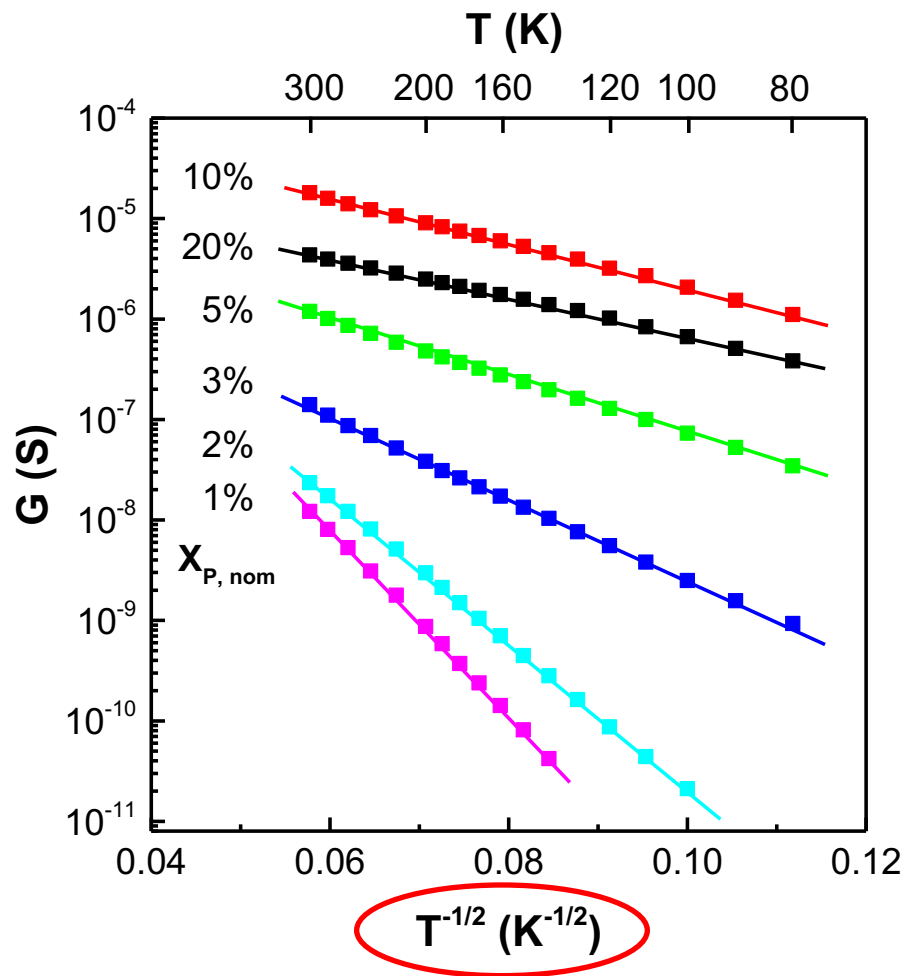
$$\lambda_F \approx \rho/2$$

$$n_c \rho^3 \approx 0.3g$$

$$k_F = \left(\frac{3\pi^2}{g} n \right)^{1/3} \quad \lambda_F = \left(\frac{g}{3\pi^2 n} \right)^{1/3}$$

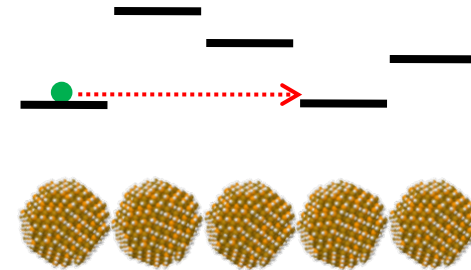
material	g	n_c (cm ⁻³)	n_{mott} (cm ⁻³)
Si	6	5×10^{20}	3×10^{18}
CdSe	1	2×10^{20}	2×10^{17}

T-dependent conductance in P-doped Si



Efros-Shklovskii variable range hopping

(A L Efros and B I Shklovskii, J. Phys. C8, L49 (1975))



NCs are randomly charged

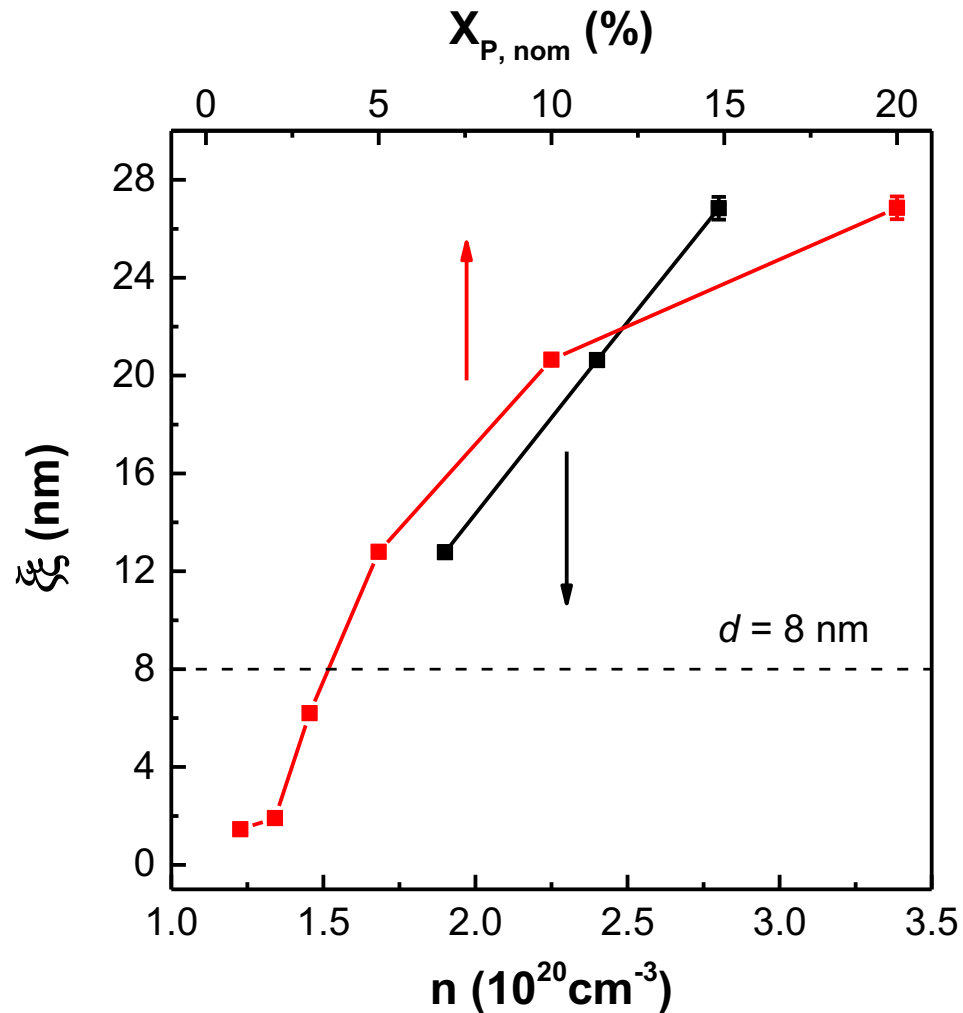
$$G \propto \exp \left[- \left(\frac{T_{ES}}{T} \right)^{1/2} \right]$$

characteristic temperature:

$$T_{ES} = \frac{2.8e^2}{4\pi k_b \epsilon \xi}$$

localization length

Approaching the metal-insulator transition



T. Chen, K. Reich, H. Fu, N. Kramer, U. Kortshagen, B. Shklovskii., *Nat. Mater.* **15**, 299 (2016)





Ben Greenberg



Zach Robinson



Claudia Gorynski



Bryan Voigt



Lorraine Francis



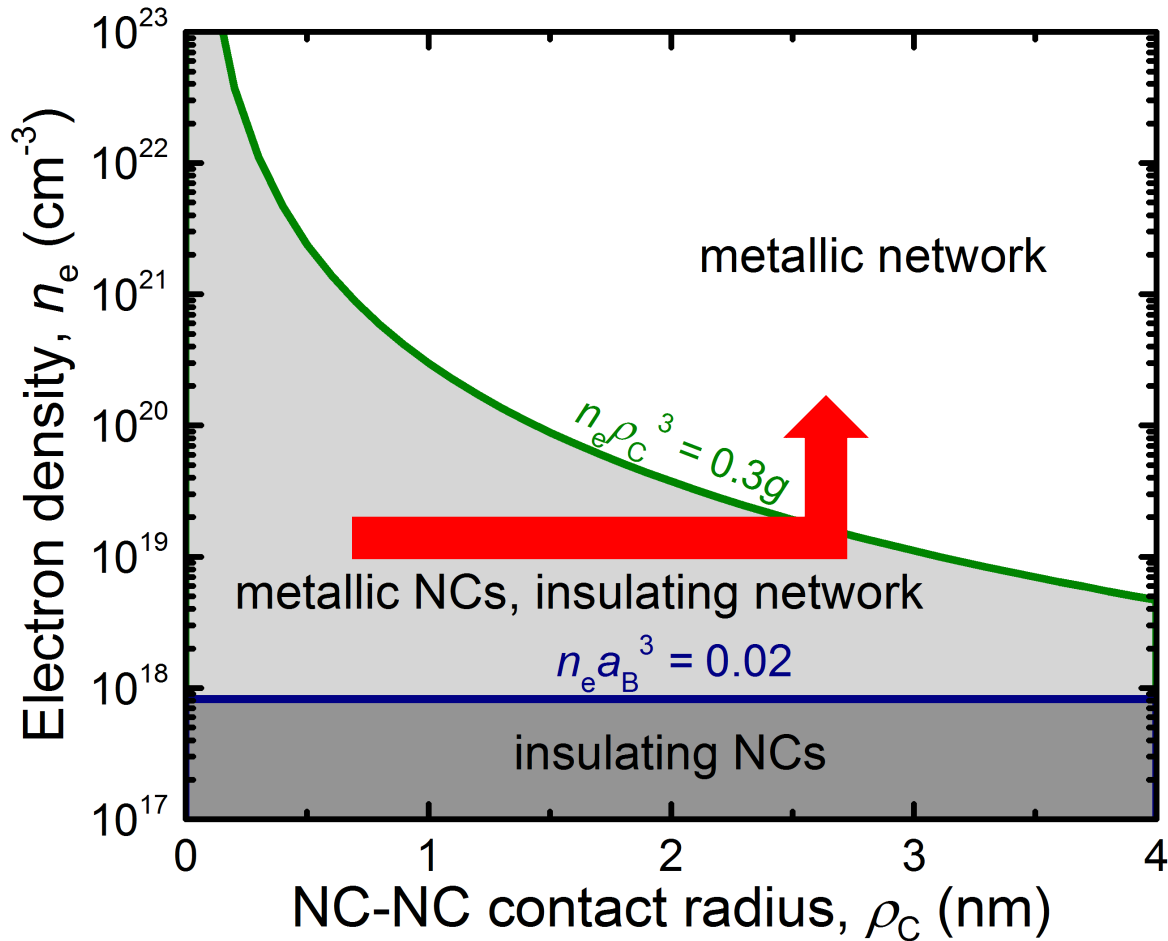
Eray Aydil

Crossing IMT in ZnO NC films?

(submitted)



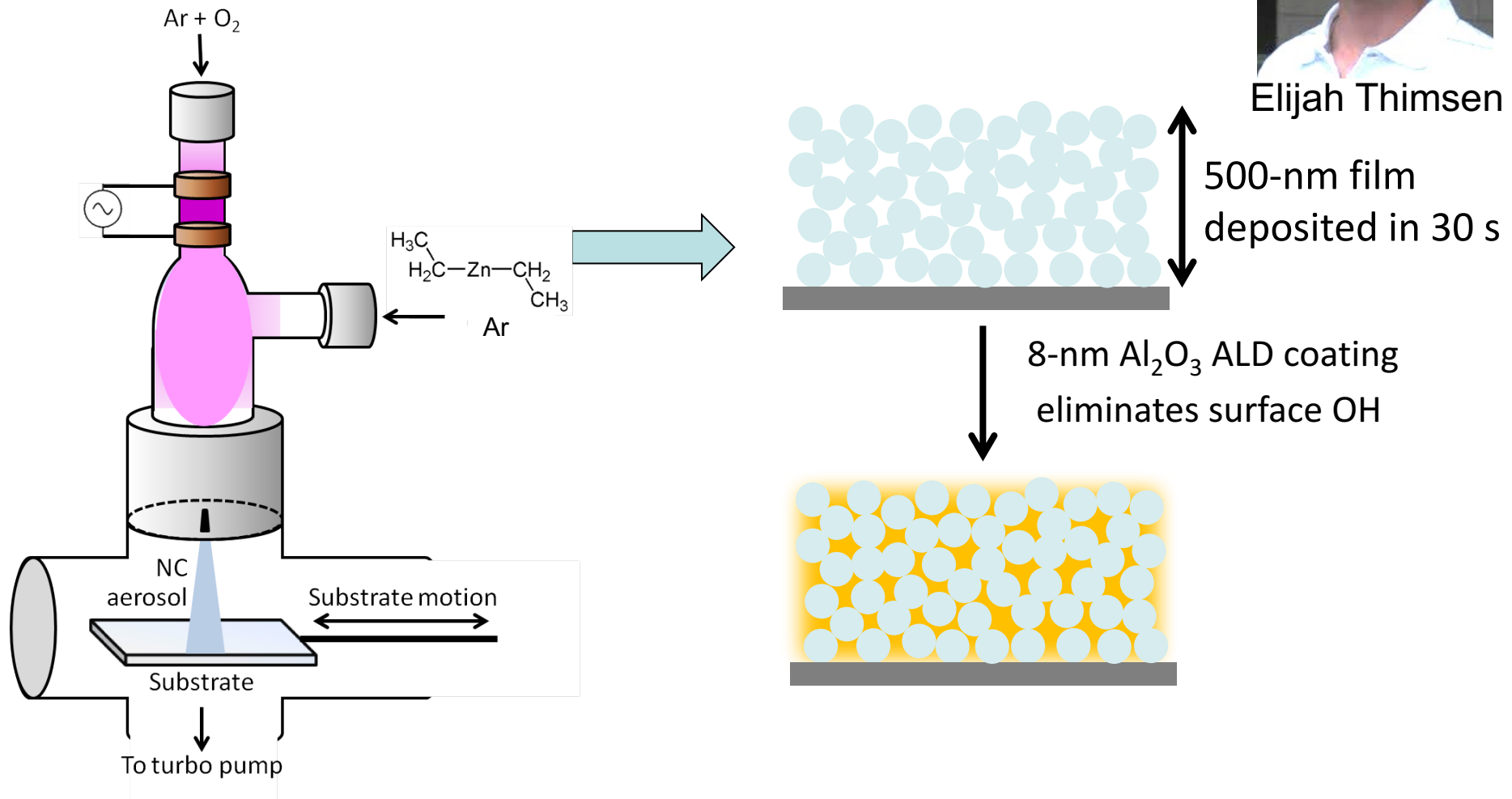
Importance of contact for metal-insulator transition



Plasma synthesis of ZnO NCs



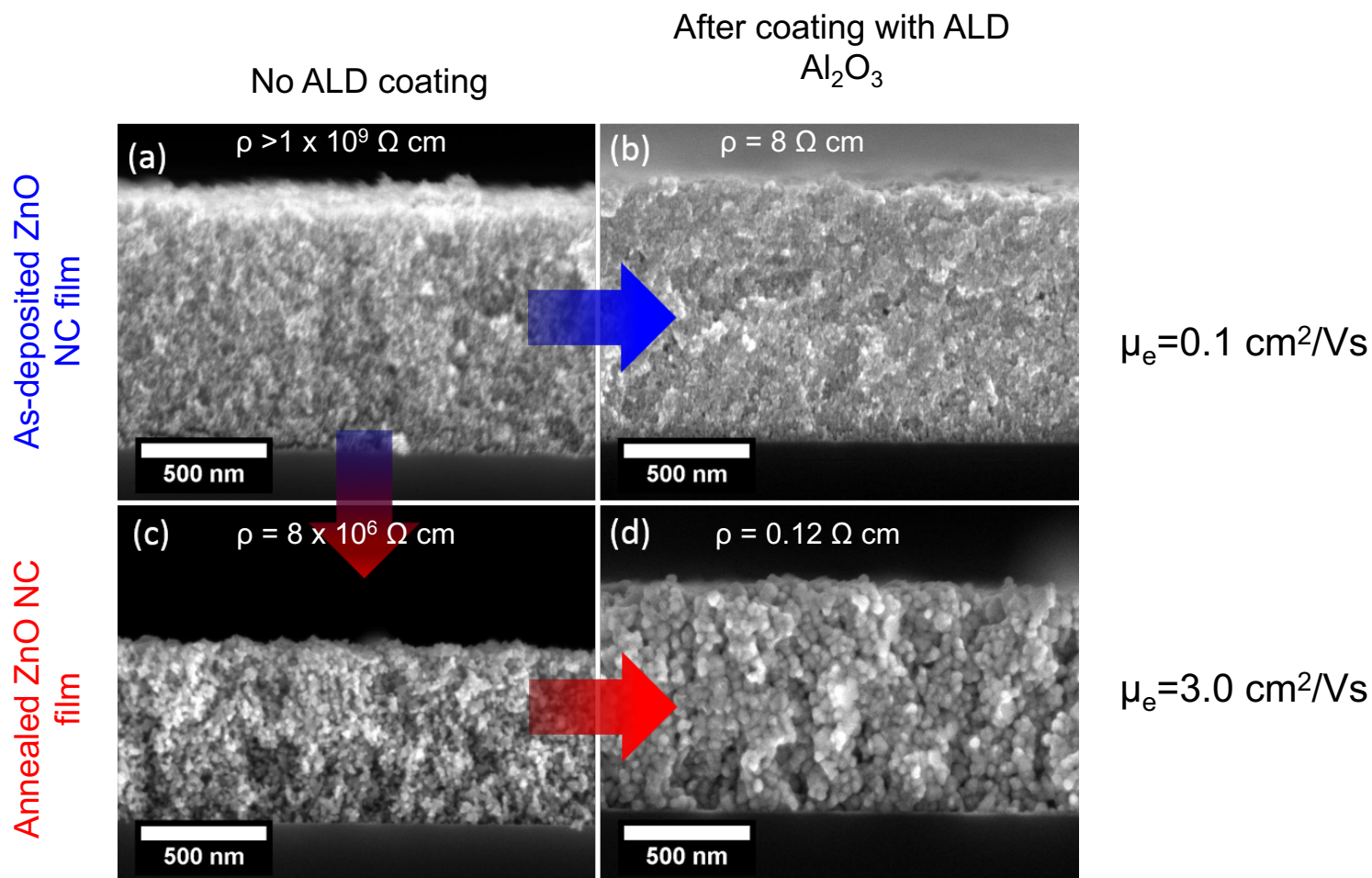
Elijah Thimsen



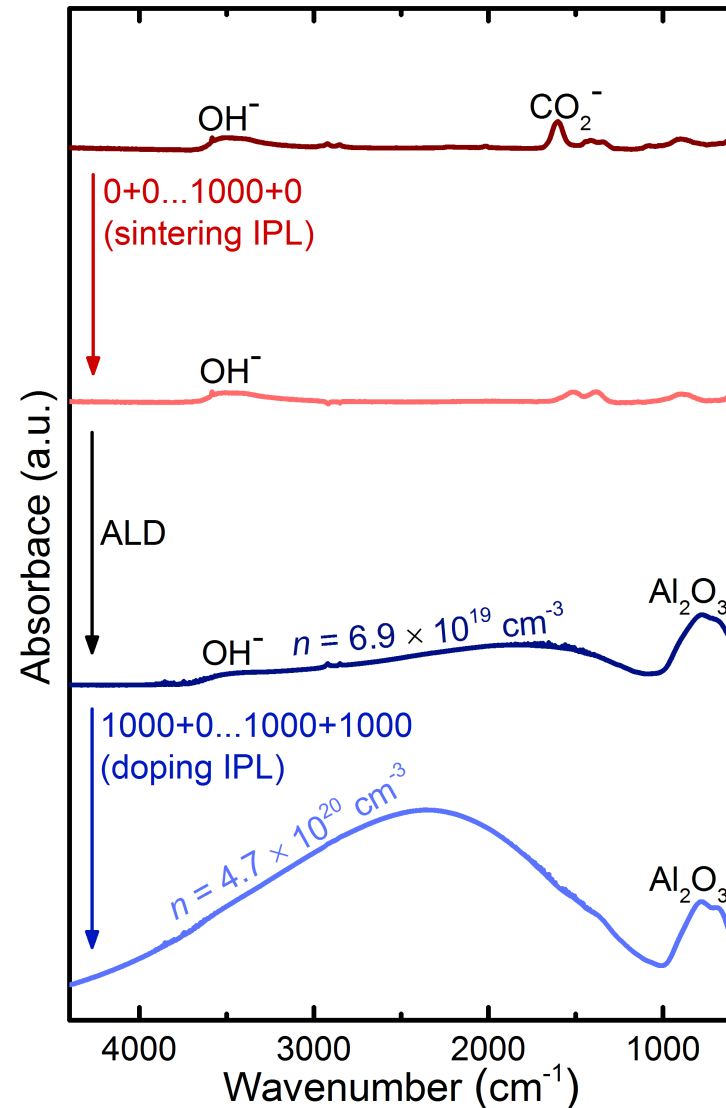
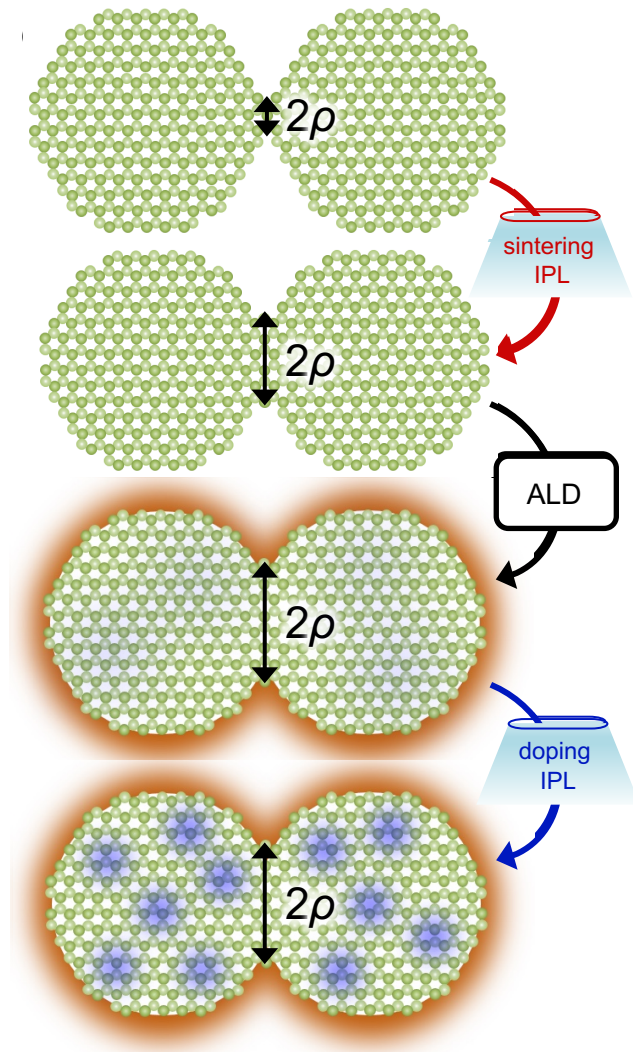
Thimsen, E., M. Johnson, X. Zhang, A.J. Wagner, K.A. Mkhoyan, U.R. Kortshagen, and E.S. Aydil, Nature Communications **5**, 5822 (2014)



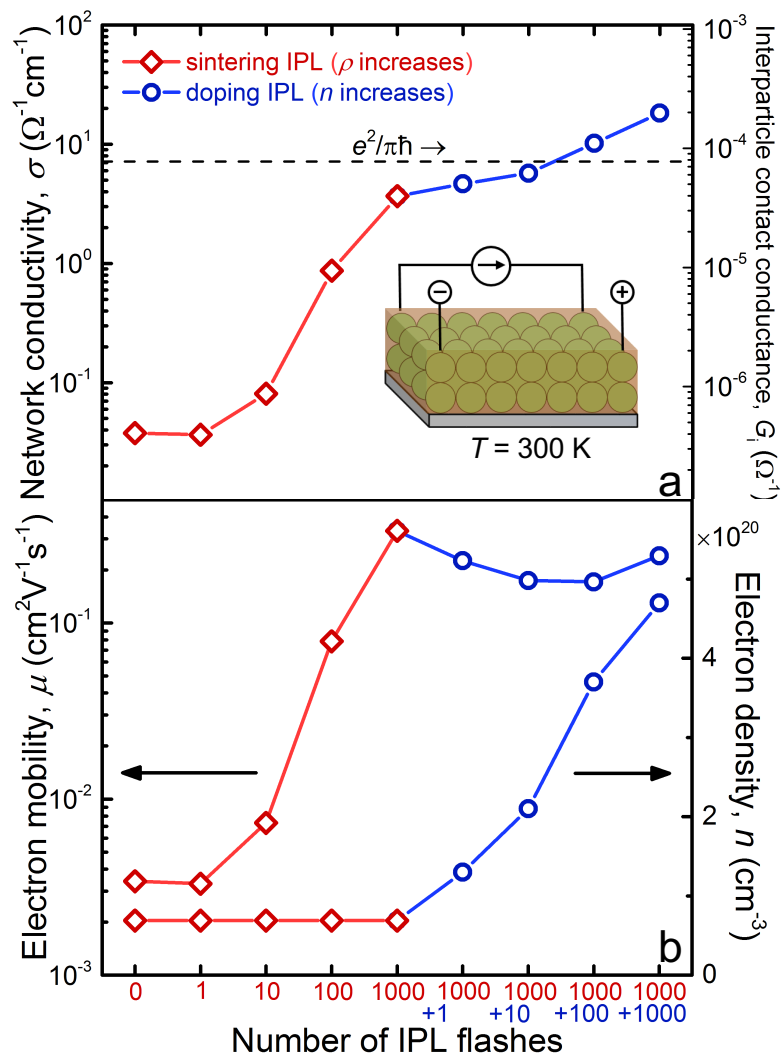
Electrical properties



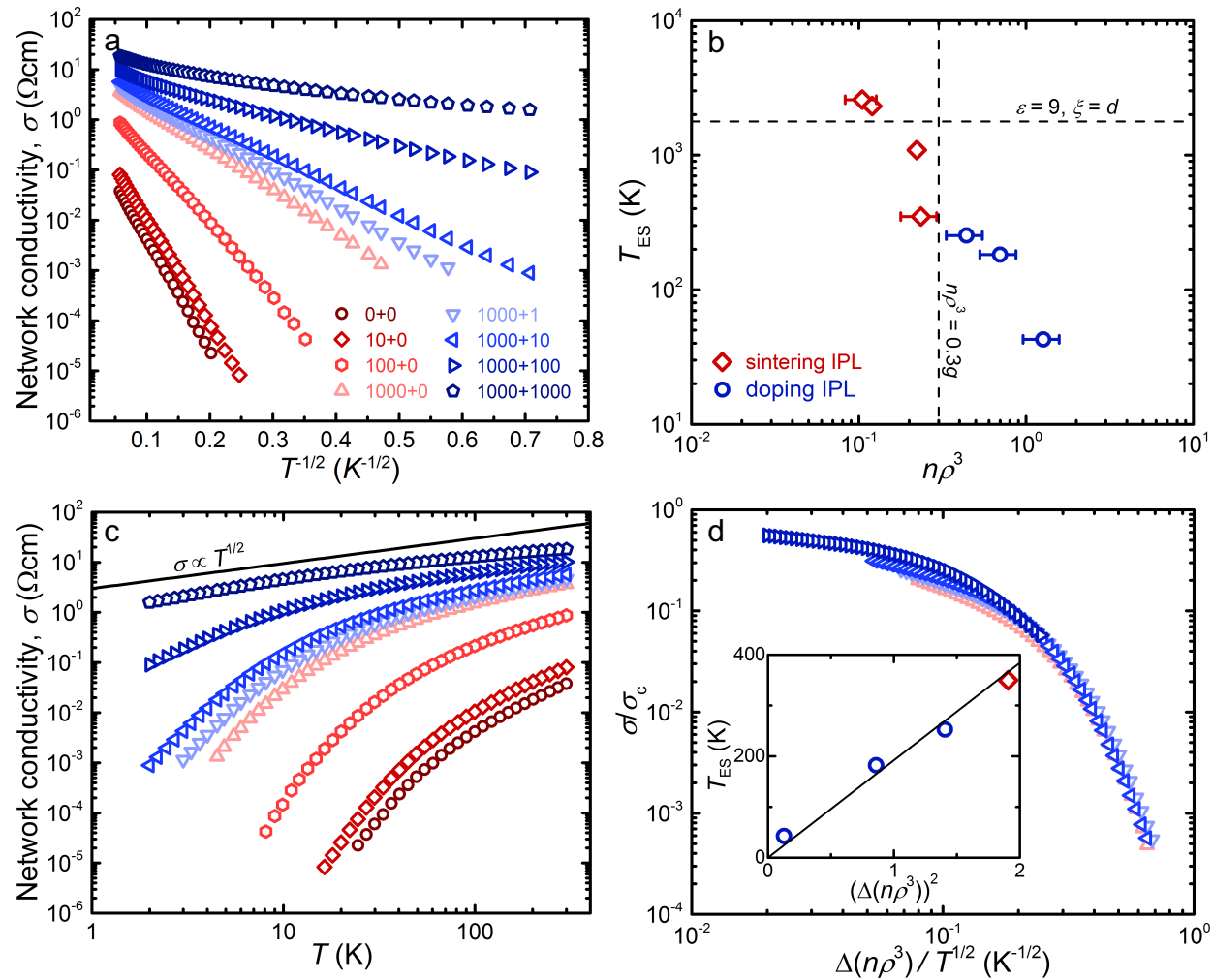
Intense Pulsed Light sintering to tune mobility and carrier density



Tuning mobility and carrier density



Approaching the insulator-metal transition



Summary

- Plasma Synthesis of nanocrystals suitable for high-melting point materials
- Plasmonic response of highly P- and B-doped Si QDs
- Theory of metal-insulator transition in doped nanocrystal films supported by measurements in P-doped Si NCs and recent measurements in ZnO NC films



Acknowledgments

